



Advanced inline characterization of crystalline silicon solar cells

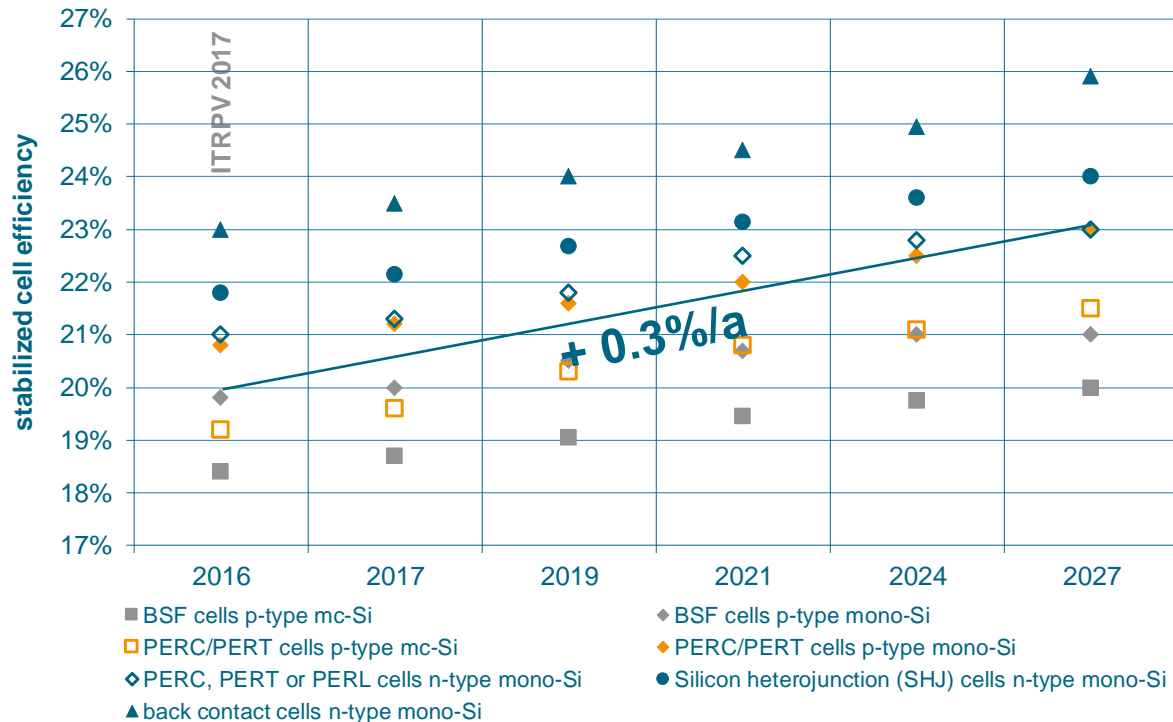
Klaus Ramspeck, [Axel Metz](#)

PV-Seminar at UNSW

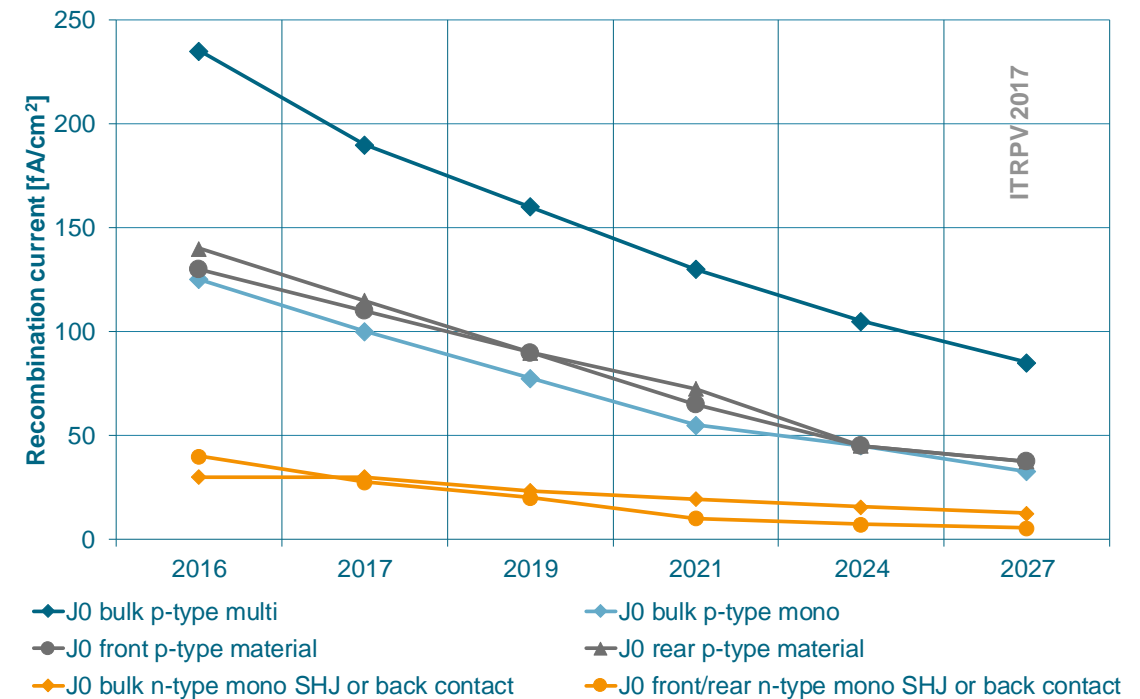
Sydney, March 24th 2017

Challenges in process and quality control

Stabilized cell efficiencies (ITRPV 2017)



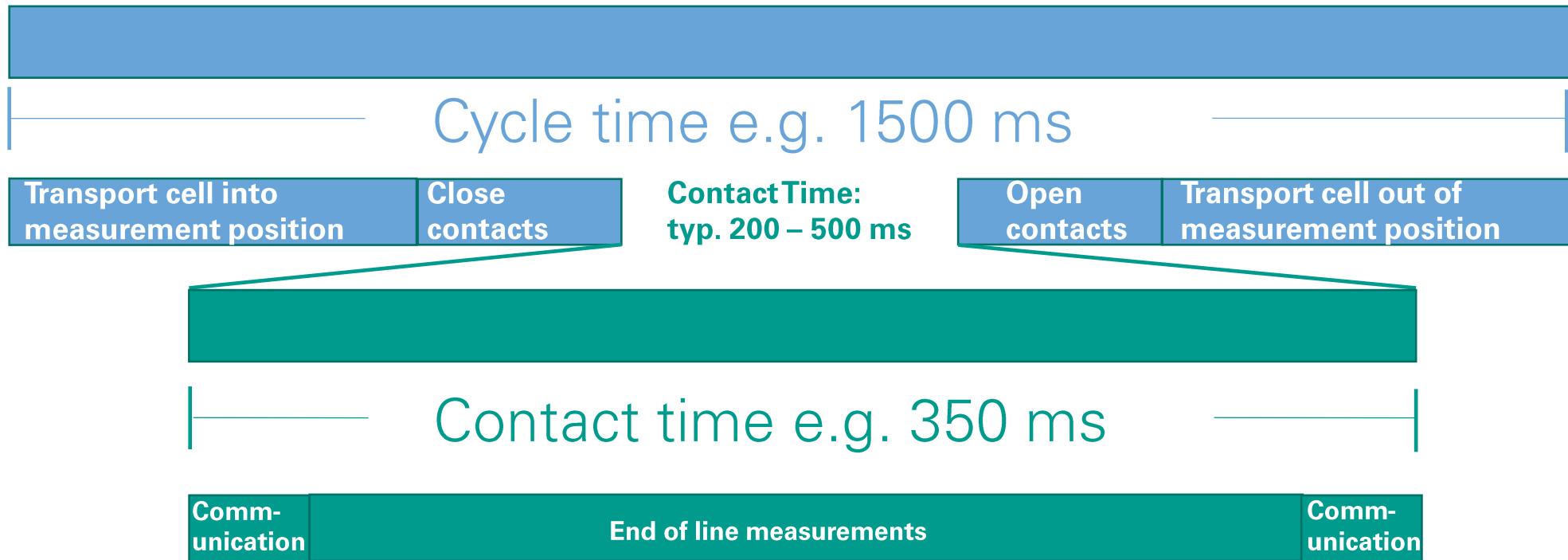
Recombination current densities (ITRPV 2017)



Increasing capacitance effects

Increasing material/process sensitivity

Challenges in process and quality control

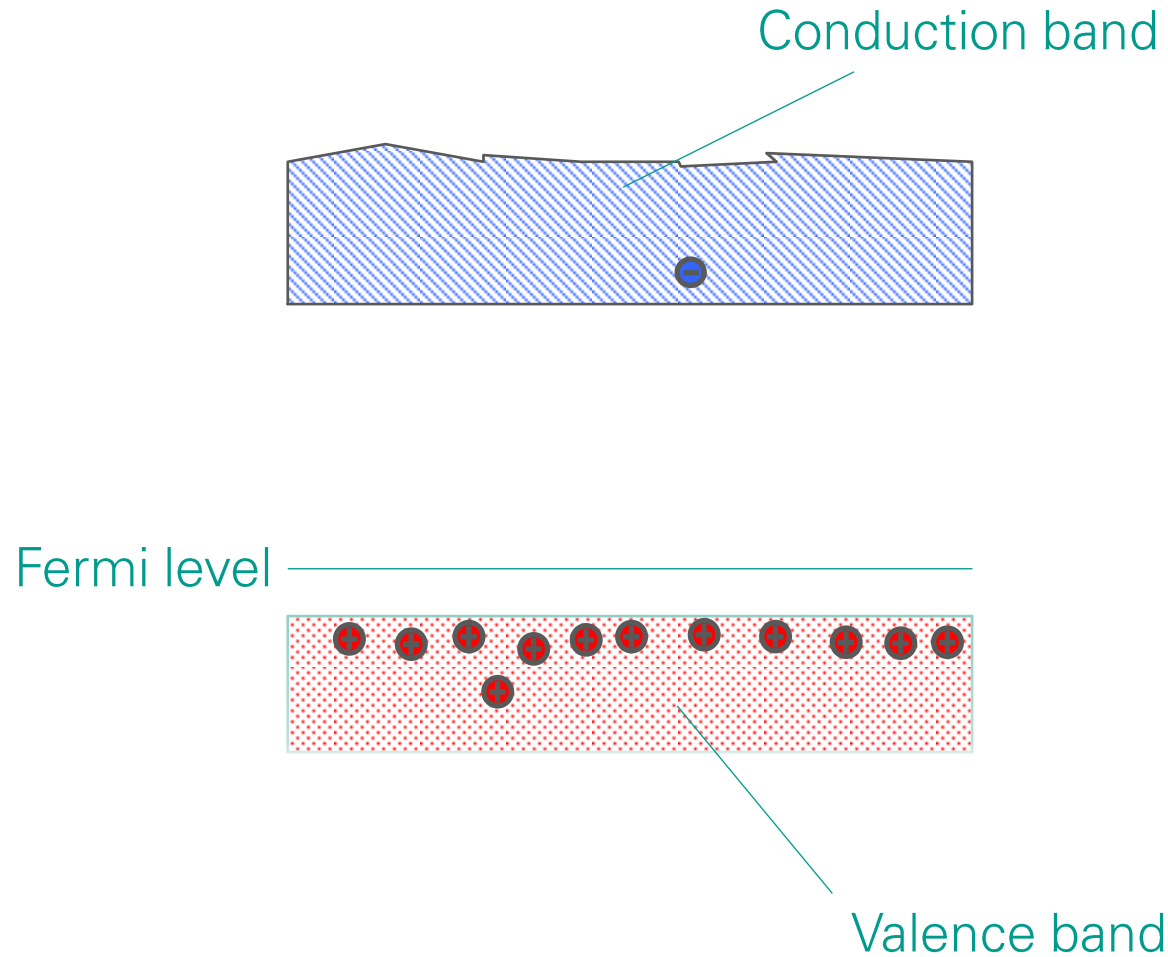


All measurements for quality and process control in cell testing **must be performed within contact time**

- How to deal with **capacitance effects**?
- **Defect detection** by EL -imaging
- **Hotspot detection** by IR thermography
- **Control of metallization process** by grid resistance measurement
- **Detection of recombination losses** by inline spectral response
- How to measure **bifacial cells**?
- Contacting of **busbarless cells**
- **Conclusion**

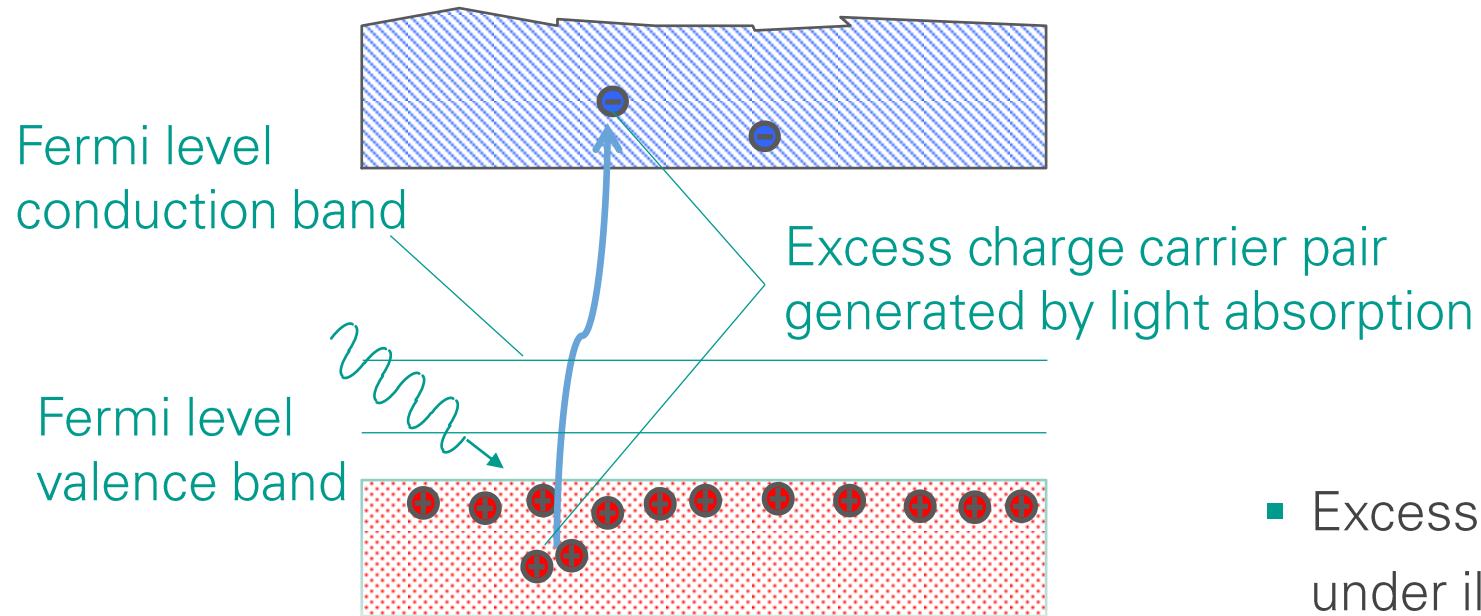
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Background – where does solar cell capacity come from . h . a . l . m .



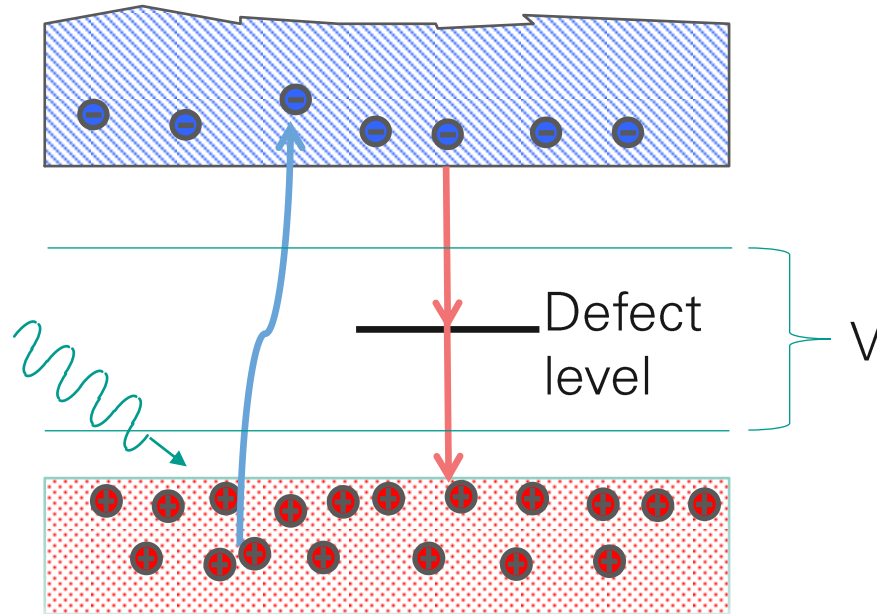
- P-doped silicon in equilibrium
- Excited charge carriers in conduction band (fermi distribution)

Background – where does solar cell capacity come from . h . a . l . m .



- Excess charge carriers generated under illumination

Background – where does solar cell capacity come from . h . a . l . m .



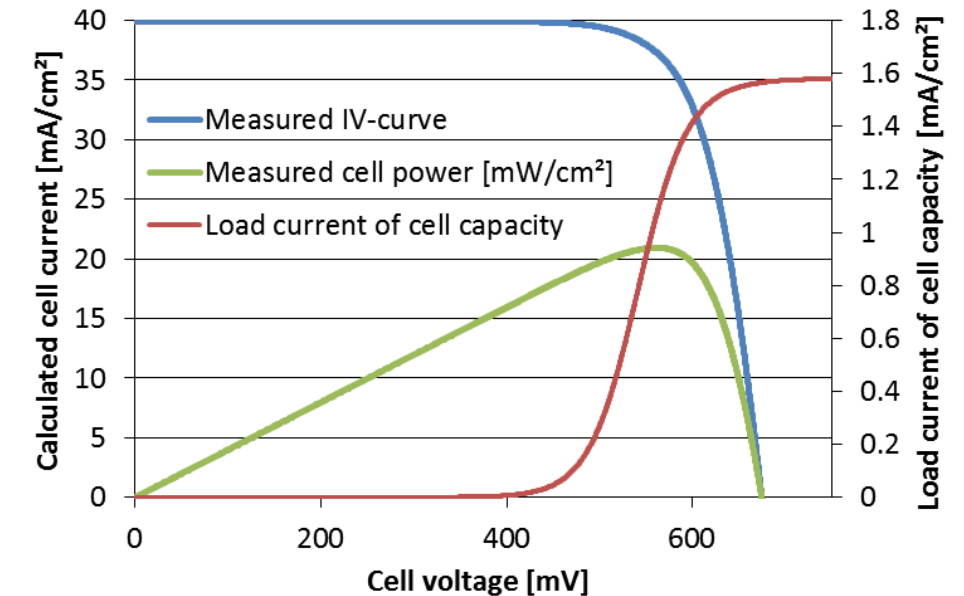
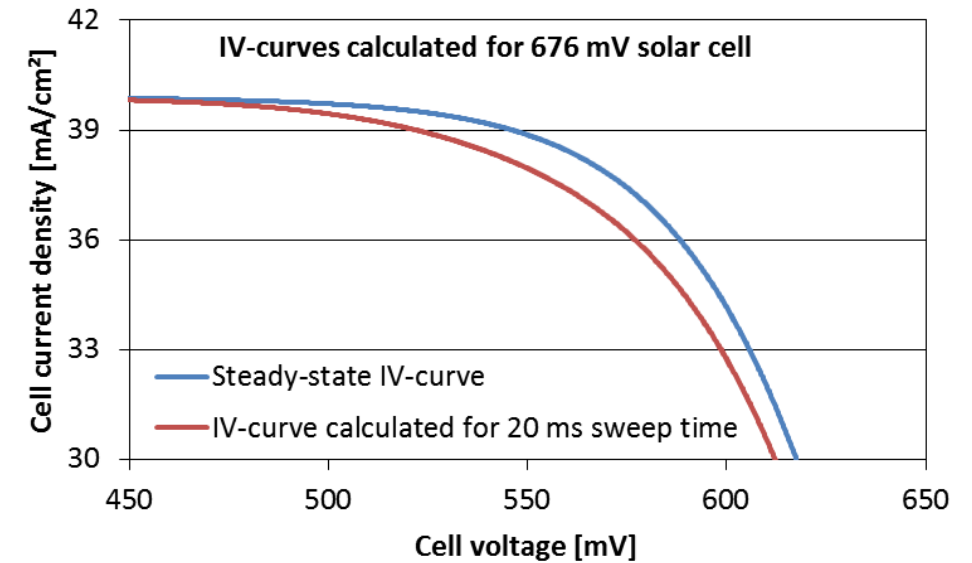
- Equilibrium under illumination:
Generation rate (G) = Recombination rate (U)

- $\tau = \Delta n / U$
- $\Delta n \sim \Delta Q \sim C_{\text{diff}}$
- $\Delta n \sim \mathbf{\exp(V/V_t)}$

Δn excess carrier density
 τ charge carrier lifetime
 ΔQ generated excess charge
 C_{diff} diffusion capacitance
 V separation of Fermi levels

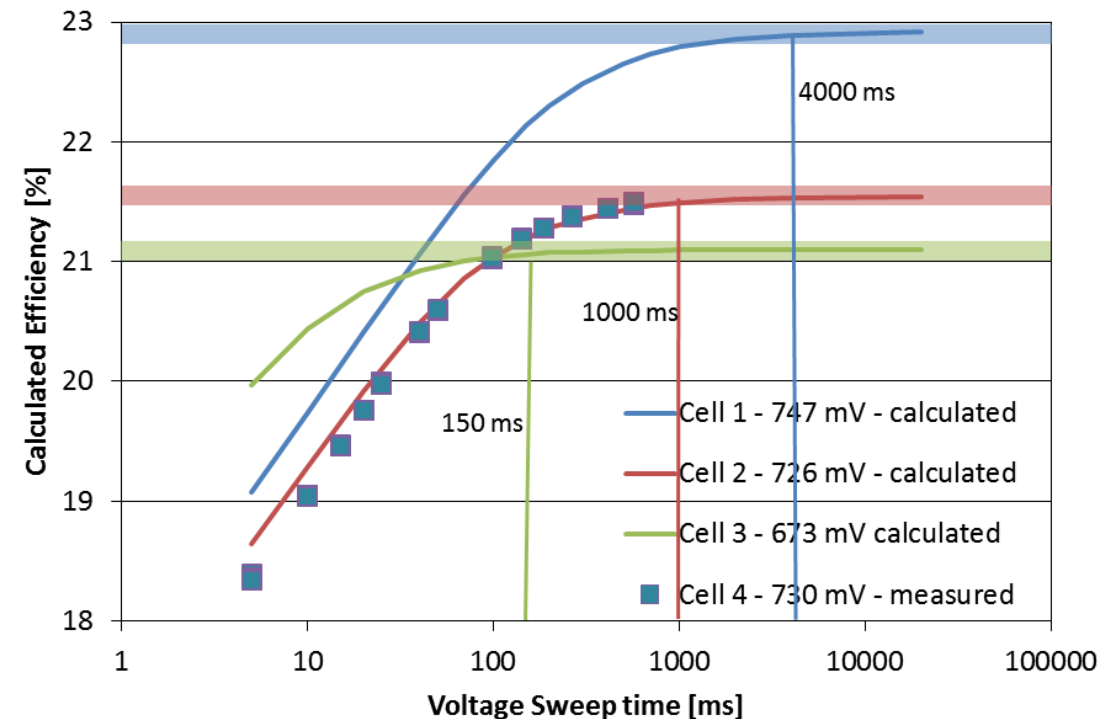
The impact of solar cell capacity on measurement of electrical parameters

- Charging the cell capacity reduces the current delivered by the cell
- Capacity is intrinsic to material
 - can't be simply avoided
- Wiring resistance and voltage sweep speed determine saturation of capacitance load current



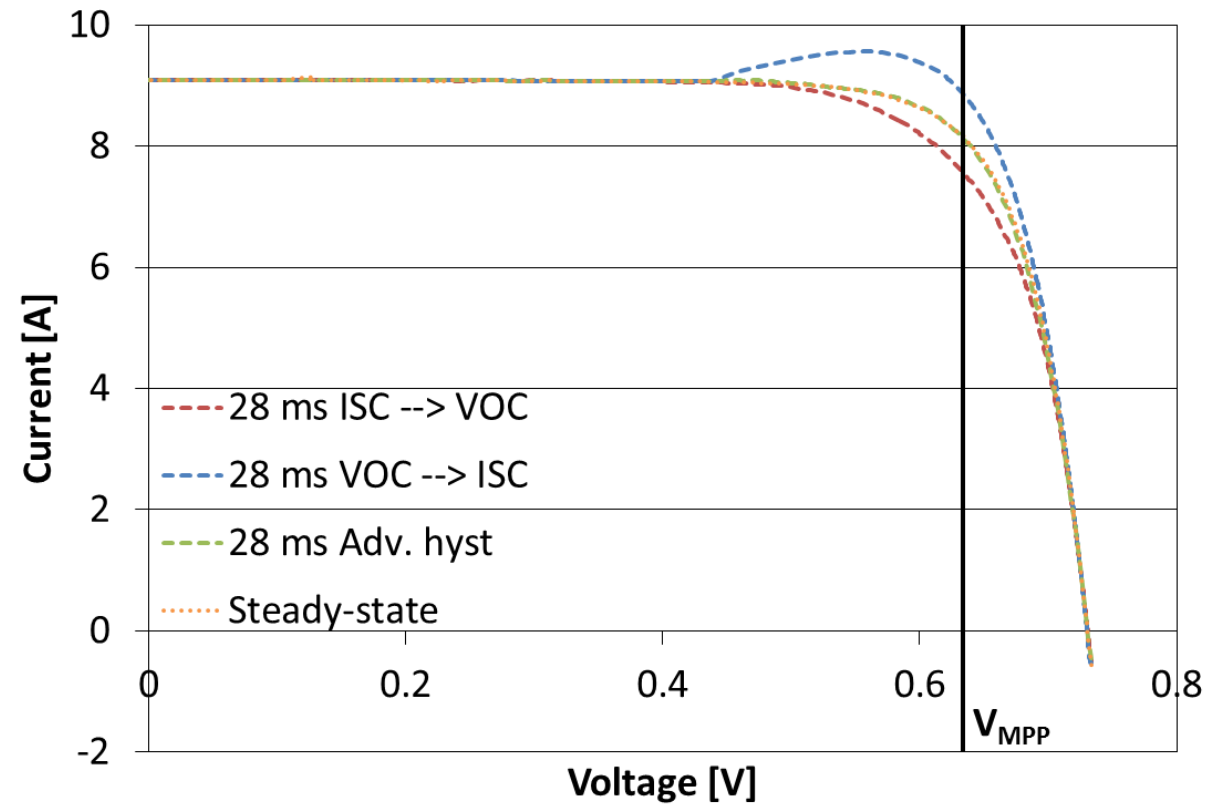
Required sweep times to avoid transient effects in standard single sweep measurements

- Accuracy requirement: $\Delta\text{Eta} < 0.05\%$
- **673 mV** cell requires approx. **150 ms**
- **726 mV** cell requires approx. **1000 ms**
- **747 mV** cell requires approx. **4000 ms**
- **Not compatible with throughput requirements!!!**
- High accuracy measurements on **high efficiency cells** in production **require** some kind of **smart approach...**

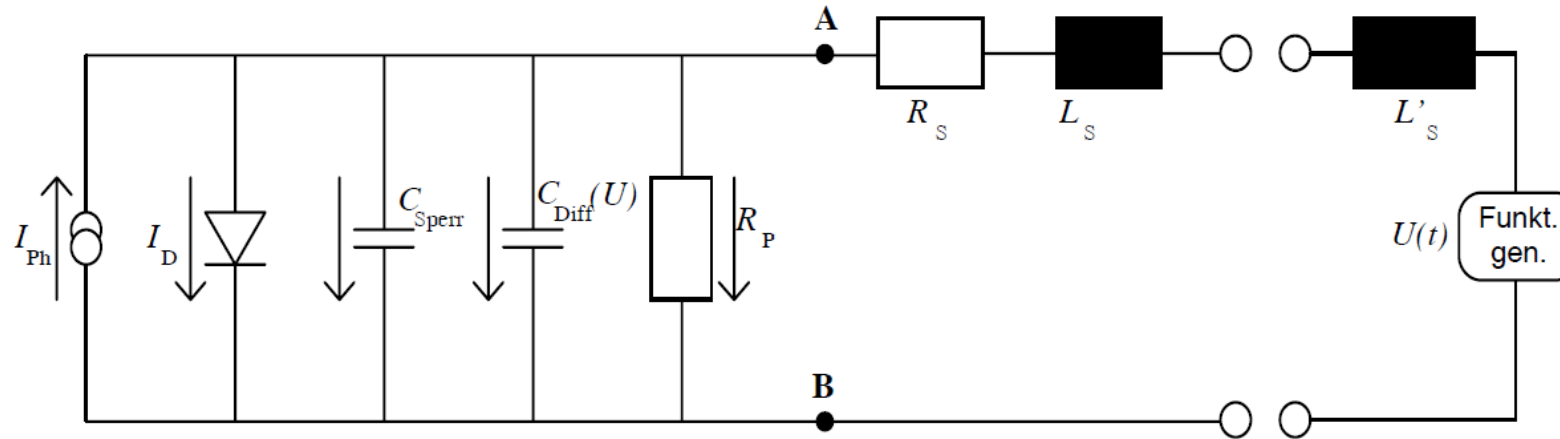


h.a.l.m. single flash hysteresis – a smart approach . h . a . l . m .

- Two voltage sweeps within **single flash** ($I_{SC} \rightarrow V_{OC}$ and $V_{OC} \rightarrow I_{SC}$)
- Measurement of effective hysteresis of I/V -curves
- Evaluation based on diode model and the two measured curves
- **No parameters to adjust**
- **Full steady-state I/V -curve** is derived self consistently



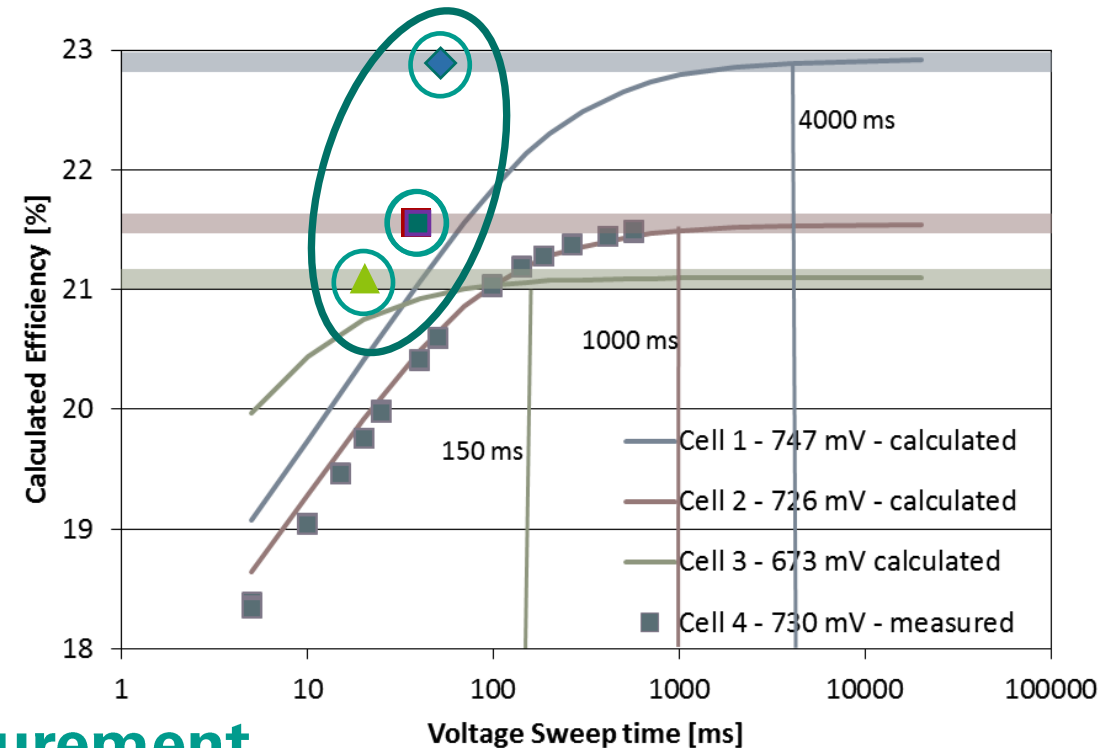
Measurement of a 730 mV cell



- Extended diode model circuit diagram as proposed by Winter et al.*
- External Voltage $U(t)$ is applied
- Cell Voltage $V(t)$ is measured between A and B
- $C_{diff}(U)$ and R_S lead to an asymmetric splitting between $I_{SC} \rightarrow V_{OC}$ and $V_{OC} \rightarrow I_{SC}$ sweep

Required sweep times to avoid transient effects in single flash hysteresis measurements

- Accuracy requirement: $\Delta\eta < 0.05\%$
2 x 12 ms
- **673 mV** cell requires approx. ~~150 ms~~
2 x 22 ms
- **726 mV** cell requires approx. ~~1000 ms~~
2 x 27 ms
- **747 mV** cell requires approx. ~~4000 ms~~



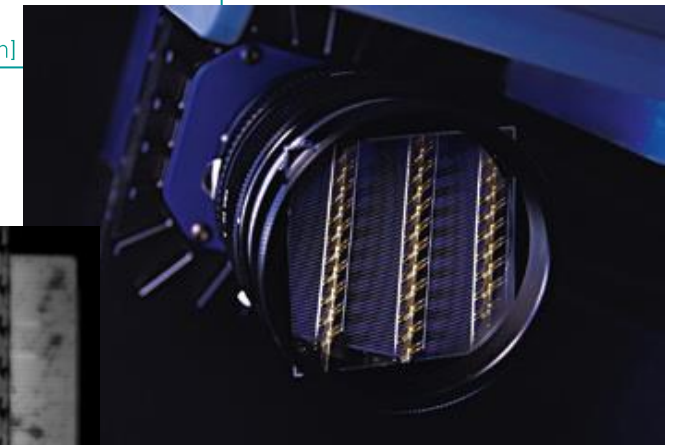
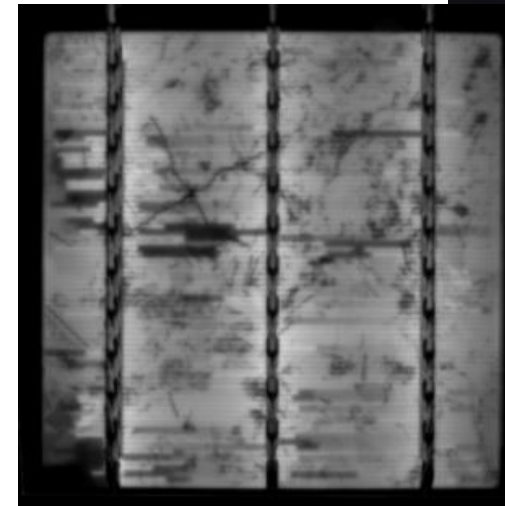
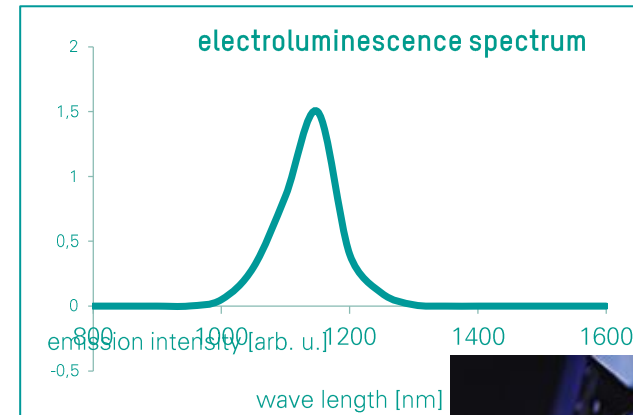
60 ms are sufficient for precise IV-measurement of solar cells with up to 750 mV in V_{oc}

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Electroluminescence (EL) imaging

What is electroluminescence imaging?

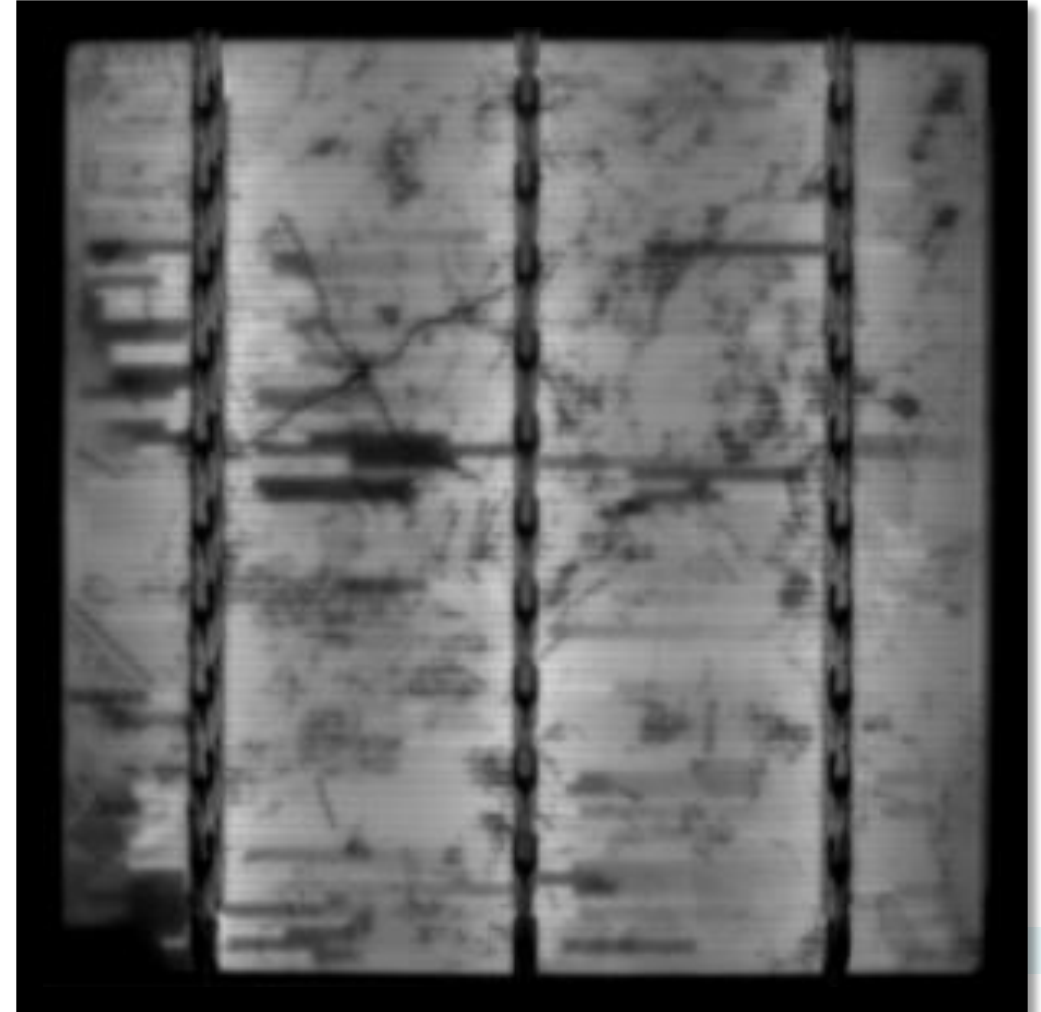
- Short wavelength infrared (SWIR) light emission in forward bias
- Light capturing with SWIR sensitive cameras
- Defect recognition by locally reduced light emission



Automated defect detection

. h . a . l . m .

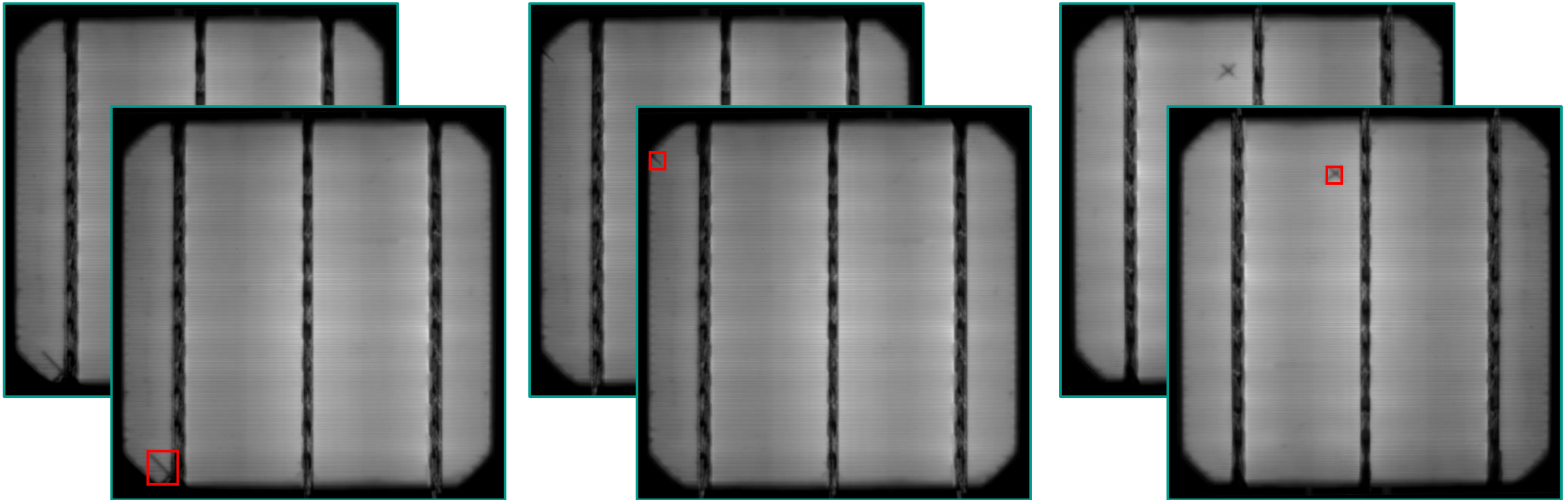
- detection quality depends on cell and wafer type
- Locally reduced light emission
 - recombination (no current)
 - blocking of light emission
 - cell defects (cracks, finger defects, etc.)
 - crystal structure
- Tool for **process** and **quality control**



Crack detection on monocrystalline solar cells

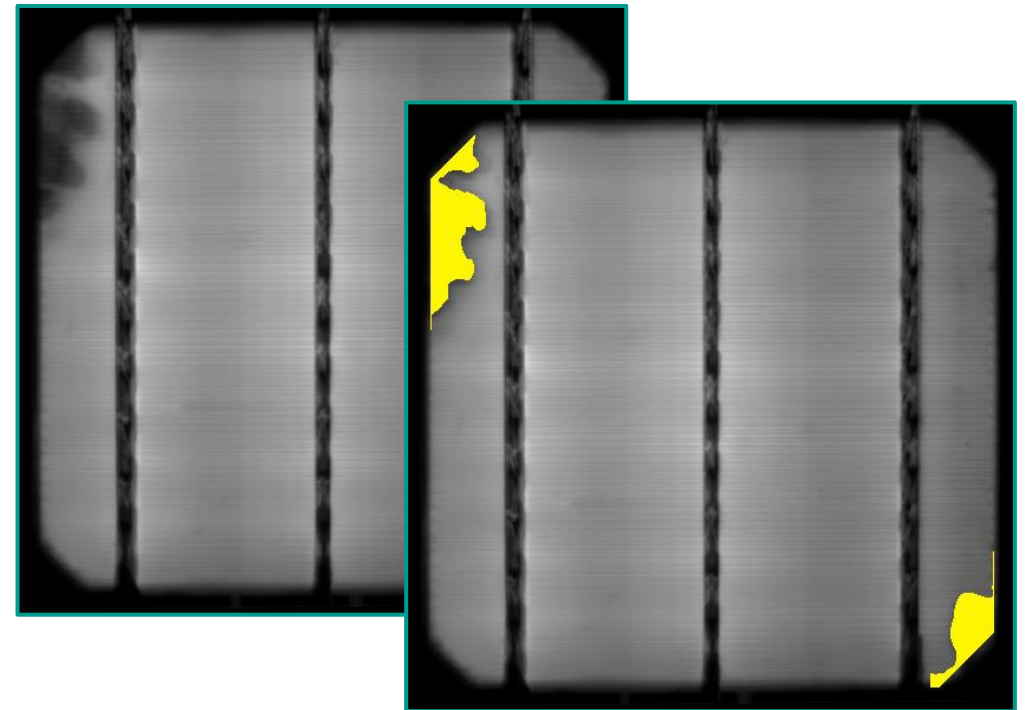
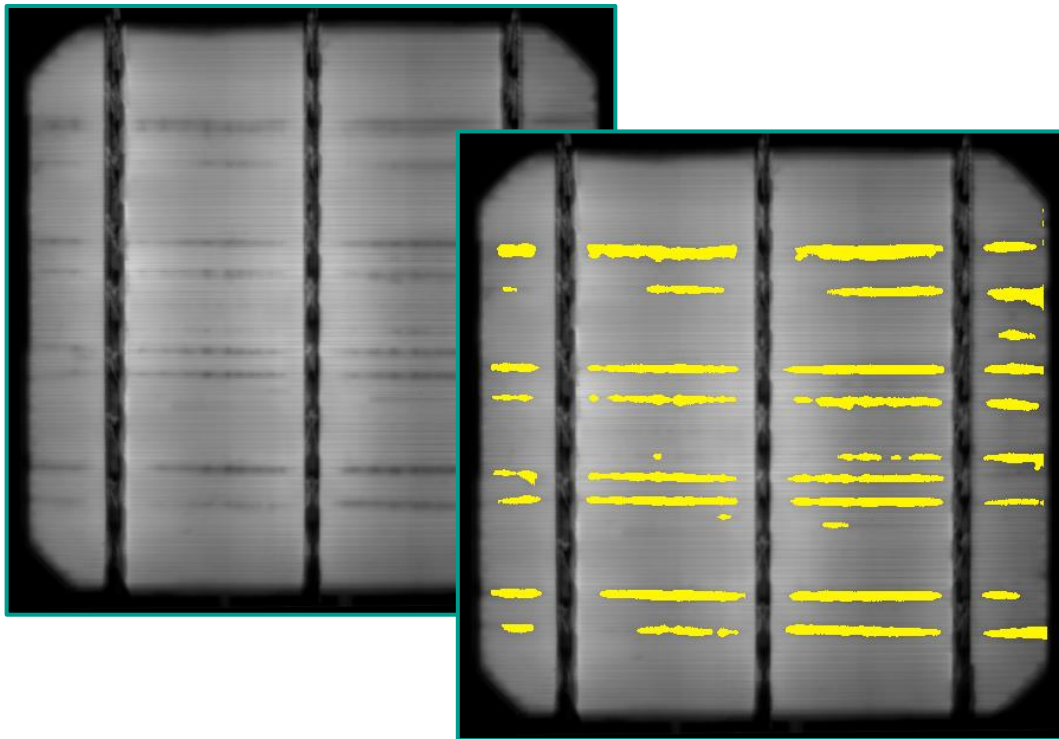
. h . a . l . m .

- **Examples:** Detected cracks



Dark area detection on monocrystalline solar cells . h . a . l . m .

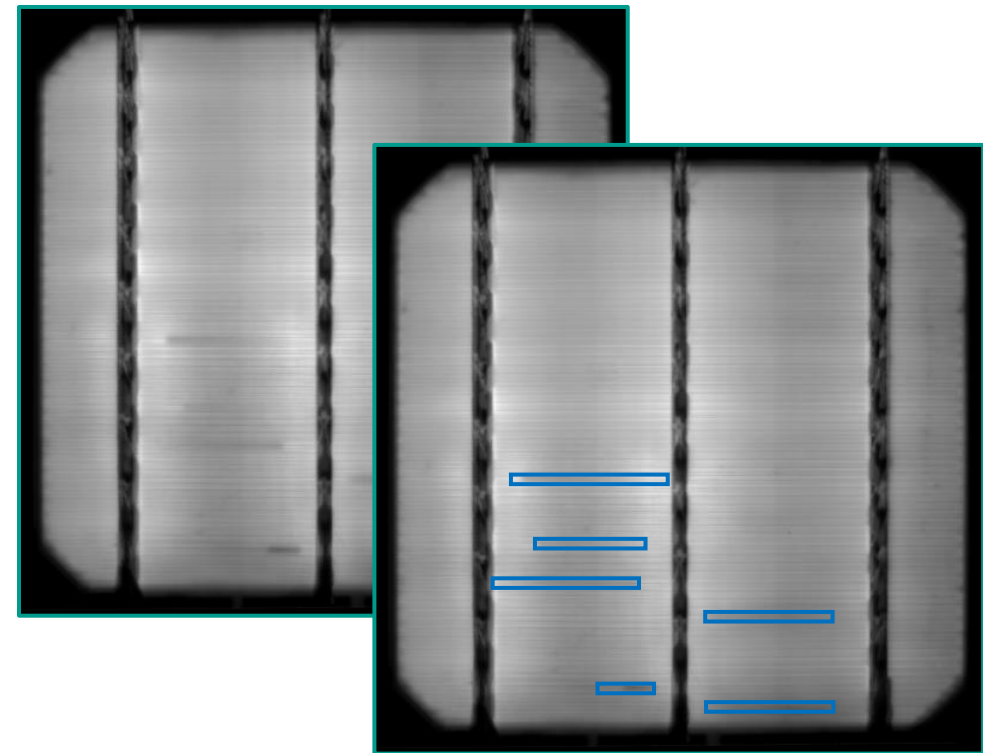
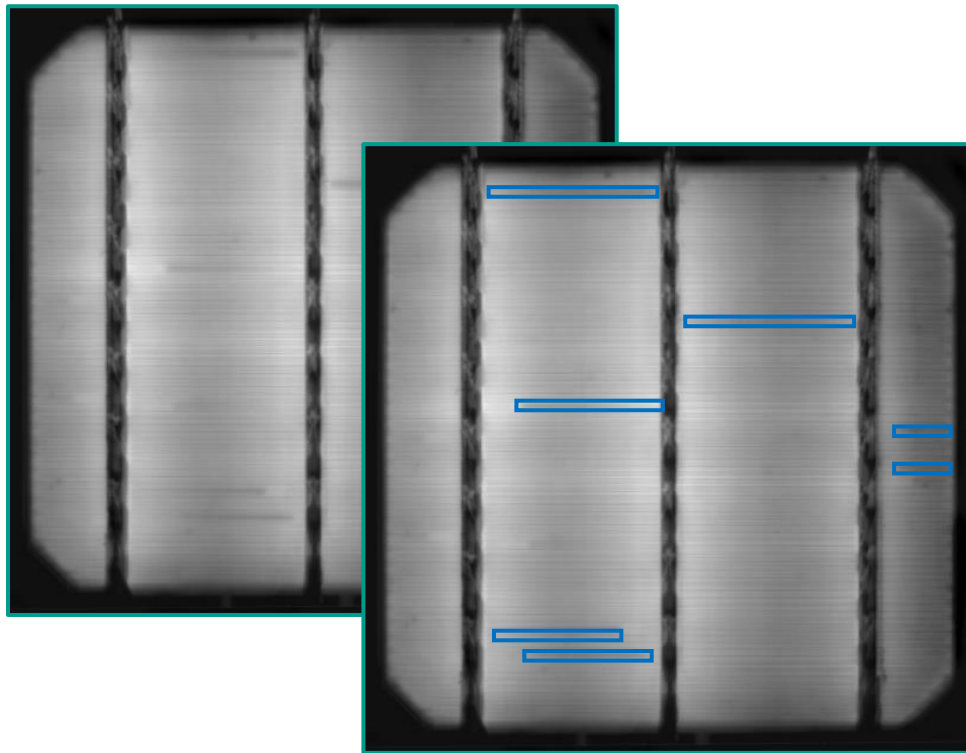
- **Examples:** Detected dark area from 5 to 8 %



Finger defect detection on monocrystalline solar cells

. h . a . l . m .

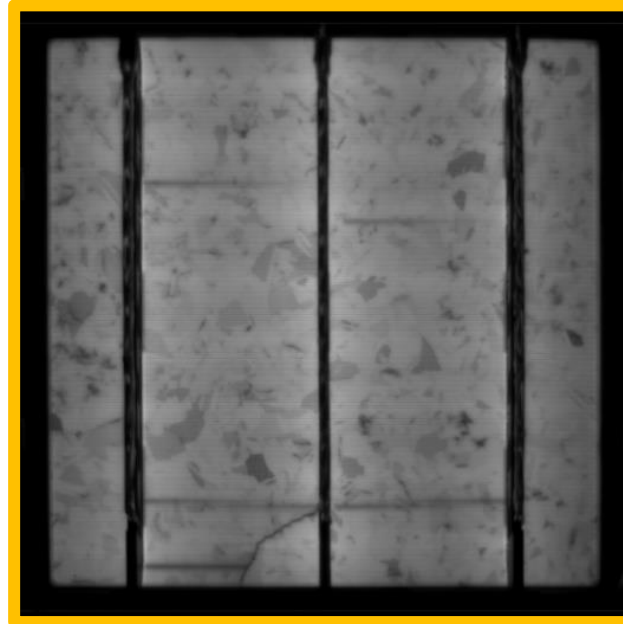
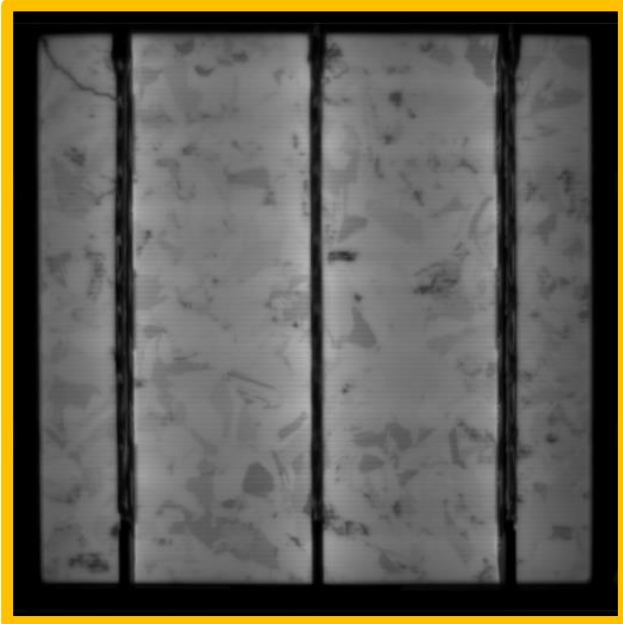
- **Examples:** Detected finger defects



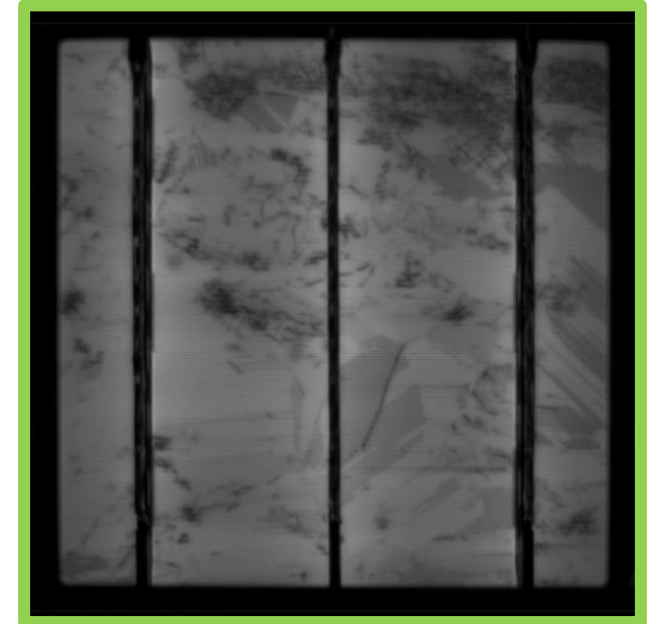
Challenge on multicrystalline cells

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Cracks



Crystal structure

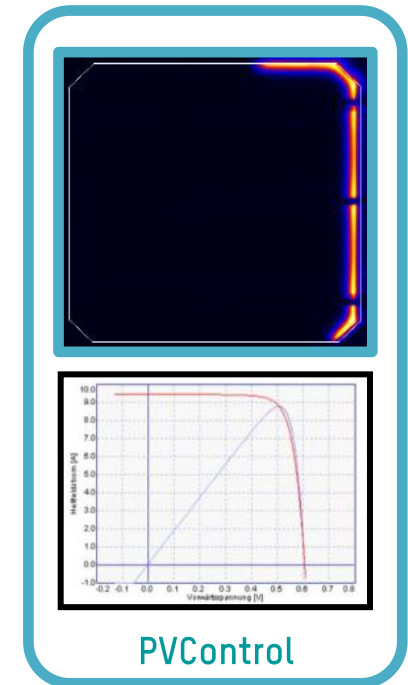
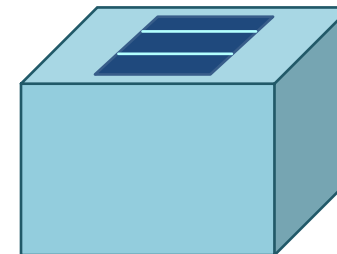
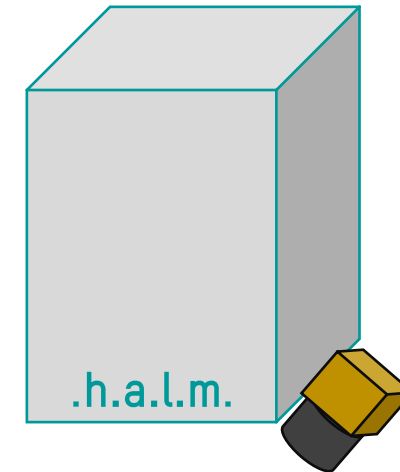


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Hotspot detection by infrared imaging

.h.a.l.m.

- High-speed infrared imaging
- Process and quality control
- Shunt detection and hot spot localization
- Available for high throughput cell testers

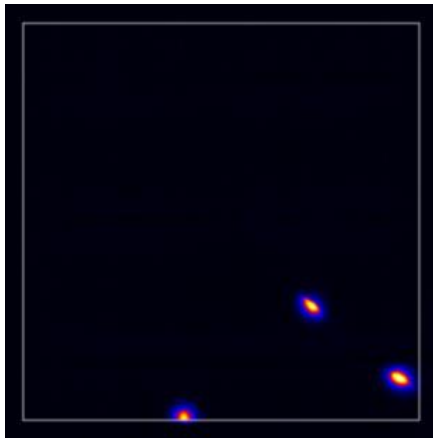


Process control by IR-imaging

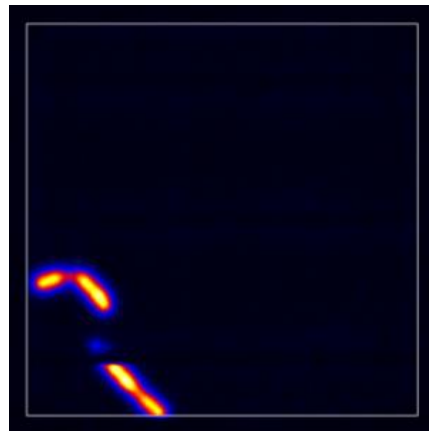
. h . a . l . m .

- localization of hot spot sources
- valuable tool for process optimization

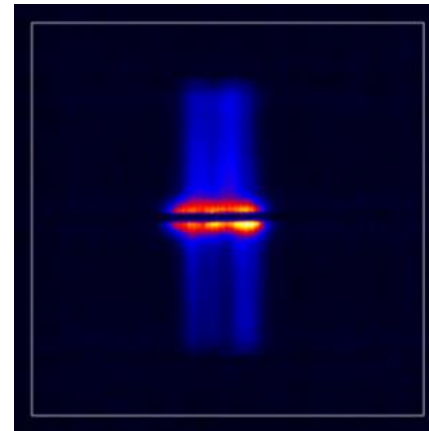
Al-contamination



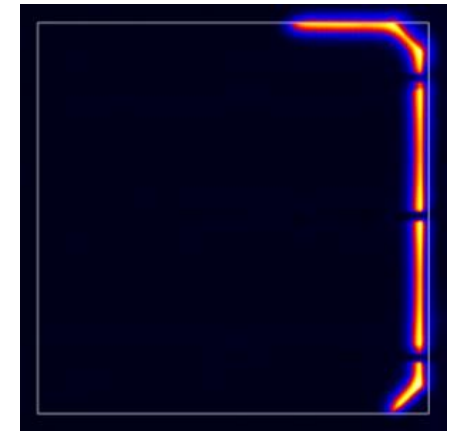
metallized crack



defect below busbar

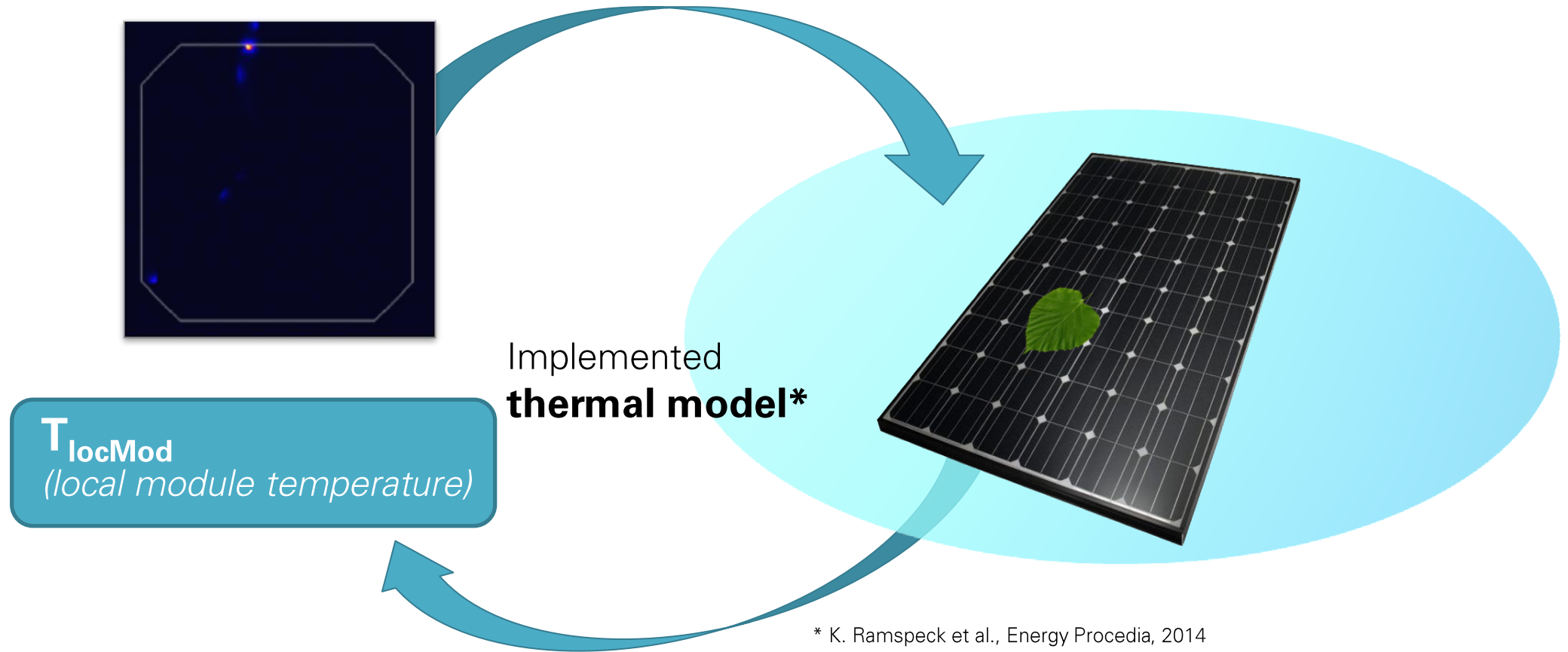


edge isolation



Advanced hotspot evaluation on module level

h.a.l.m.



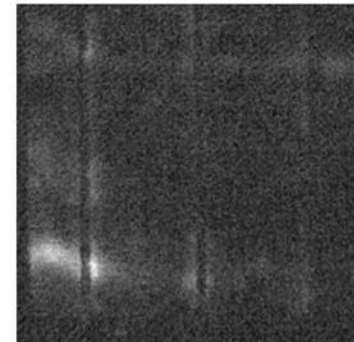
Quality control by advanced thermography evaluation

h.a.l.m.

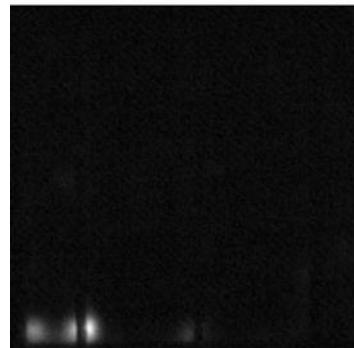
- Prediction of module temperatures in critical operating conditions (thermal model)
- Determination of really critical cells
- Reducing yield loss in cell production
- Software option for cetisPV-IR-package

Advanced thermography evaluation

- Examples of different current distributions
- Similar power dissipation but strongly differing module temperature prediction



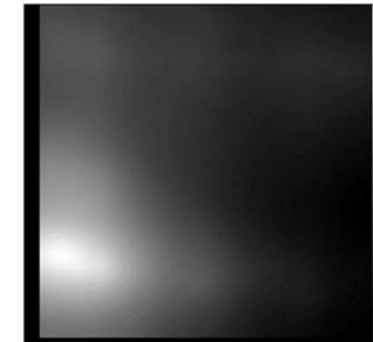
24 W power dissipation



27 W power dissipation



29 W power dissipation



77 K

0 K



169 K

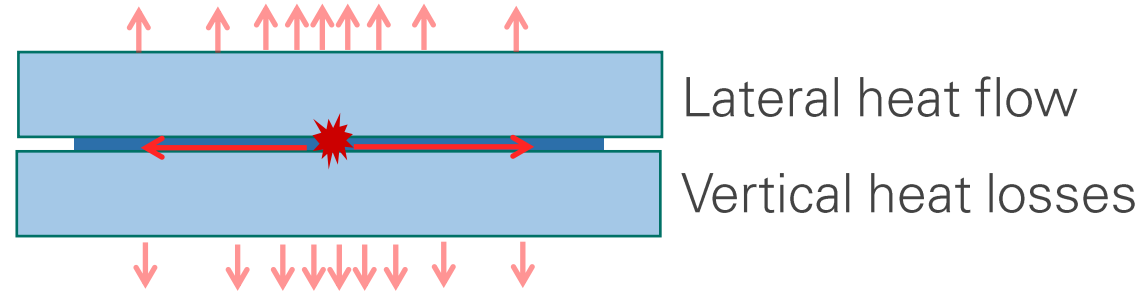
0 K



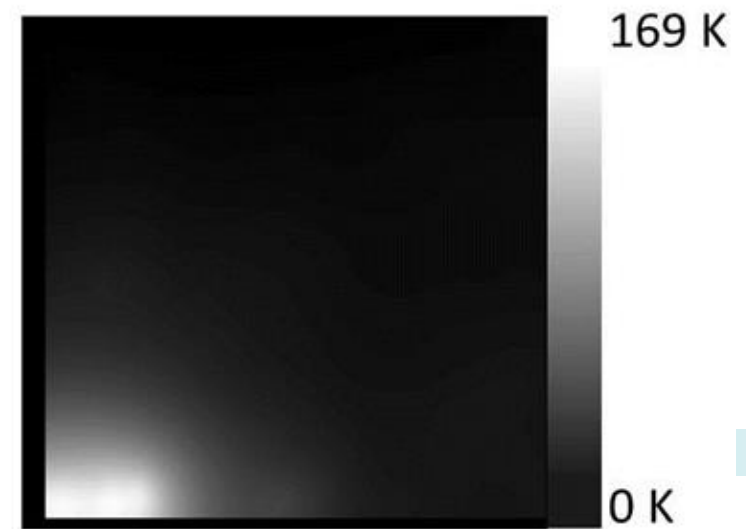
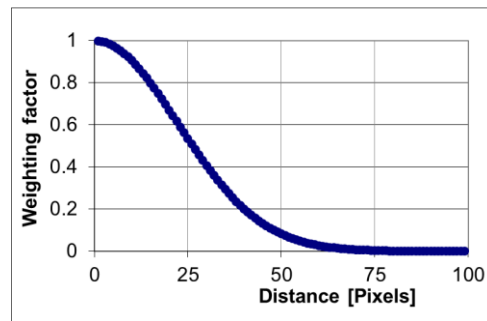
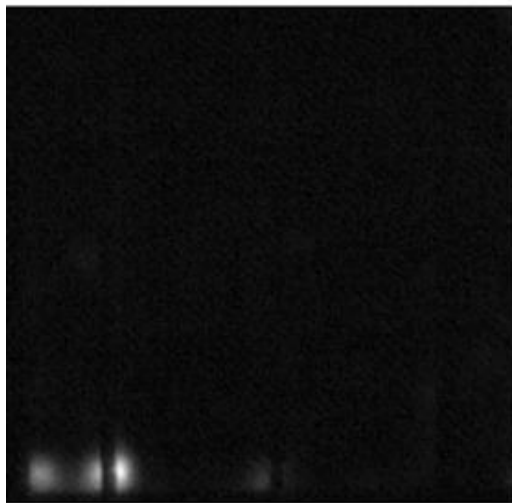
467 K

0 K

Model of advanced thermography



Radial symmetric blurr matrix

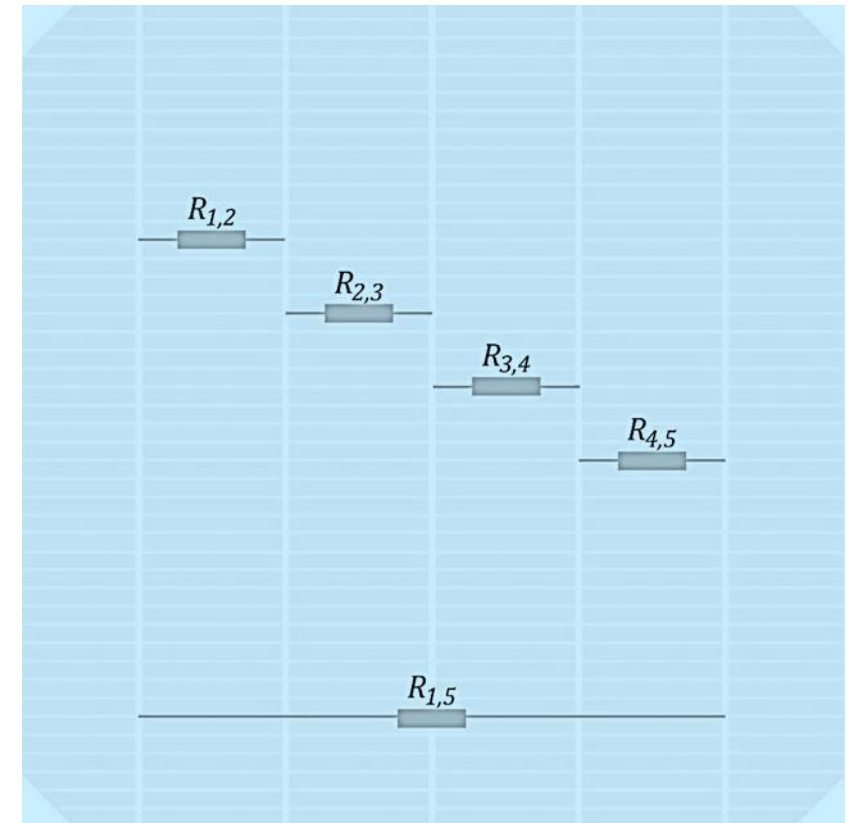
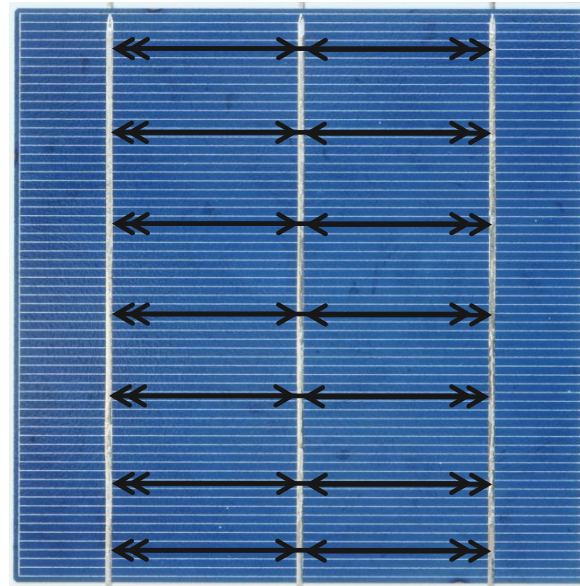


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Control of metallization process

h.a.l.m.

- Measurement of resistance between any combination of two busbars
- Monitoring of paste/printing/metallization quality
- Simple tool for process control
- Up to five busbars

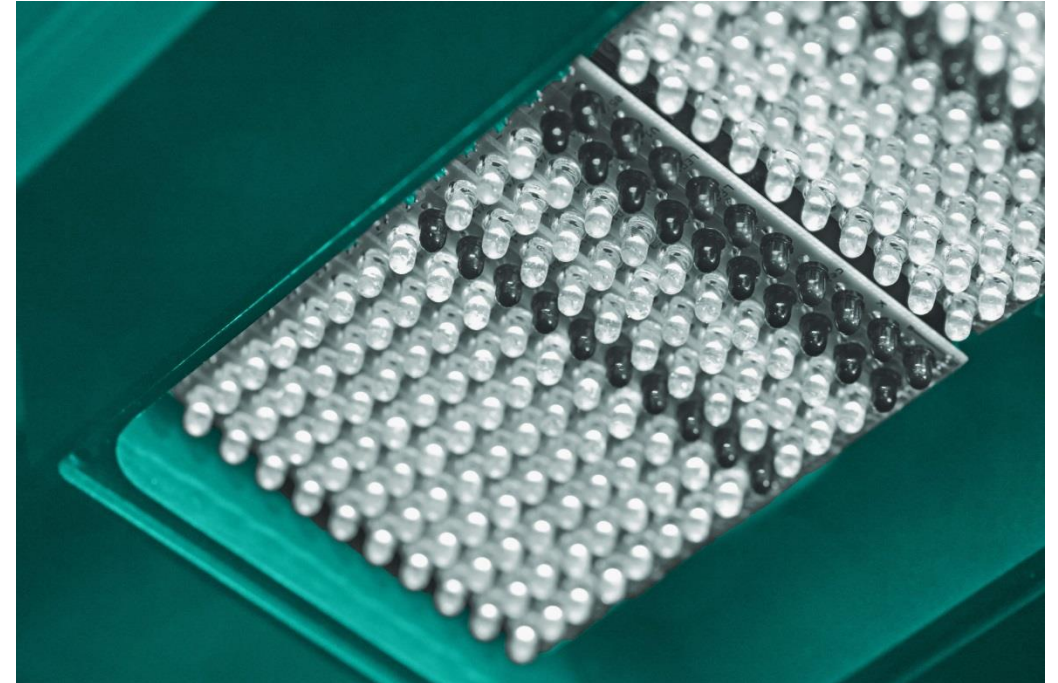


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Detection of recombination losses

h.a.l.m.

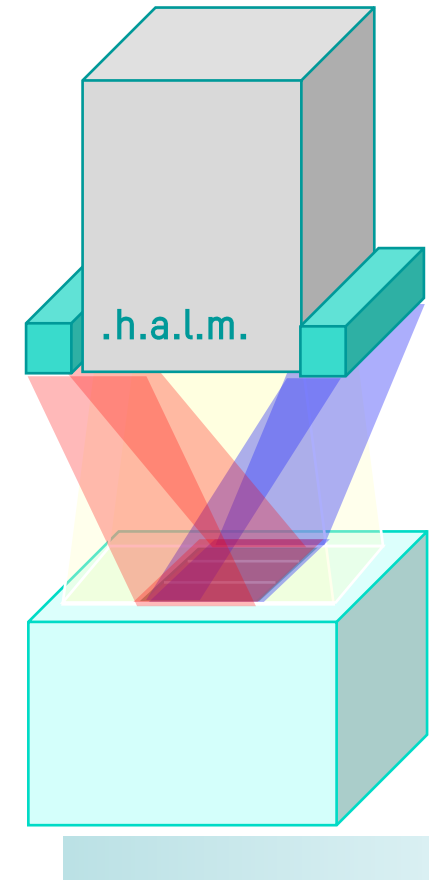
- 2-wavelength spectral response measurement for solar cells in production
- Identifying **front** and **rear** surface losses



Inline spectral response measurement

.h.a.l.m.

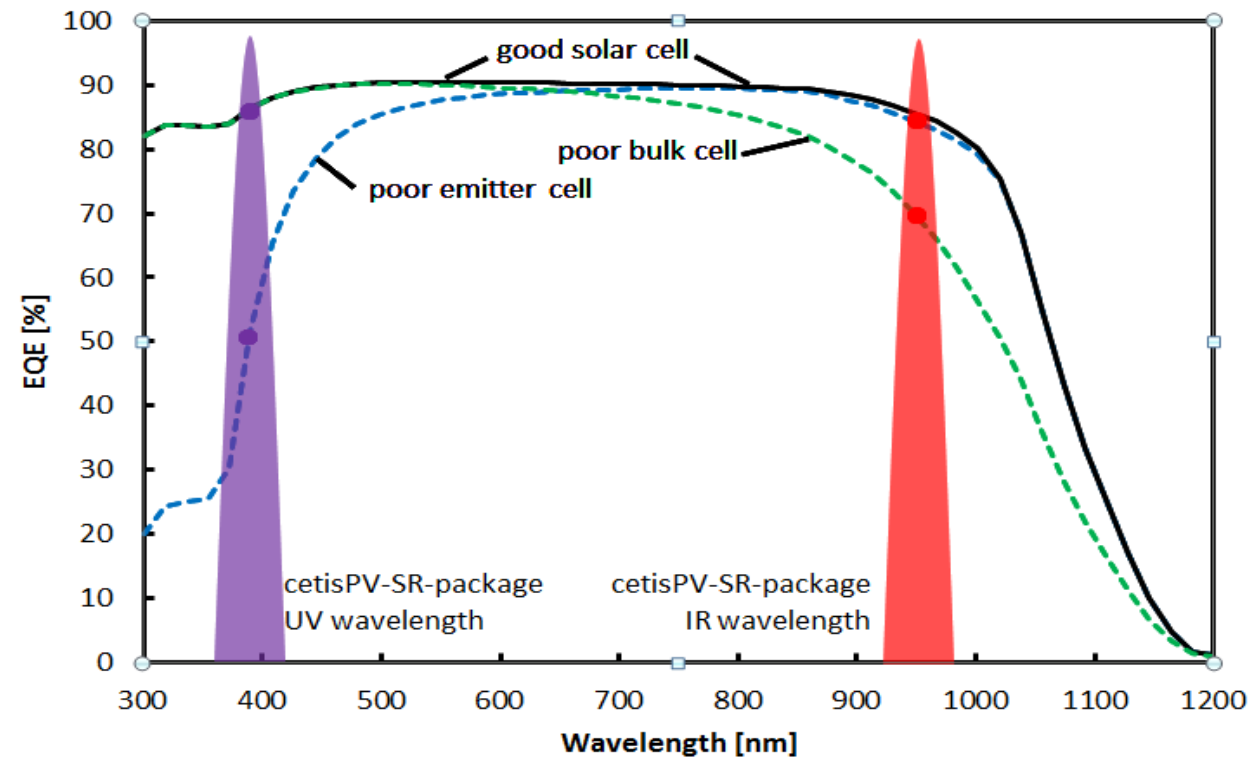
- 2 wavelengths: **390 nm (UV)** and **950 nm (IR)**
- discrimination between front and rear surface losses
- identification of deficiencies of various process steps
e.g. **anti-reflection coating, emitter diffusion, rear side passivation or metallization**
- available for high throughput



Inline spectral response measurement

h.a.l.m.

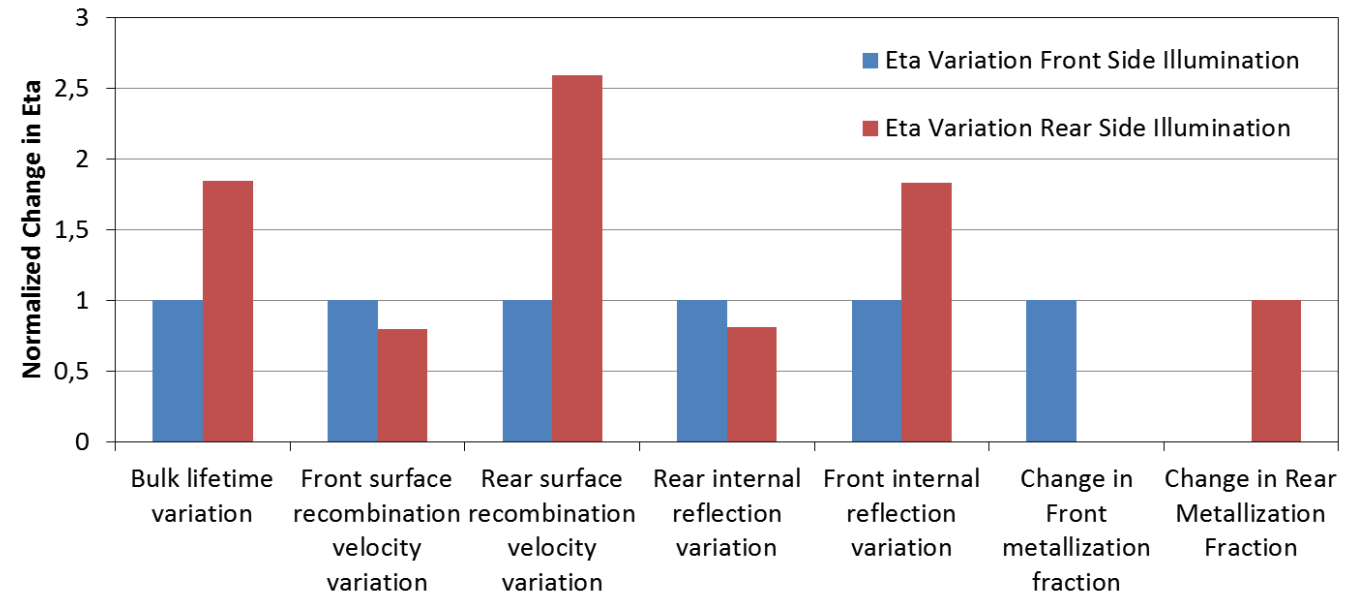
- Extremely high repeatability
- High sensitivity for front and rear-side losses
- Detects small process variations before they impact cell efficiency
- Narrow spectral distribution of light source



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Properties and bifaciality – solar cells

- Impact of solar cell parameters on front and rear efficiency is different
- Numerical values depend on cell architecture and performance
- Strongly different impact on front and rear efficiency:
Surface recombination velocity and optical parameters



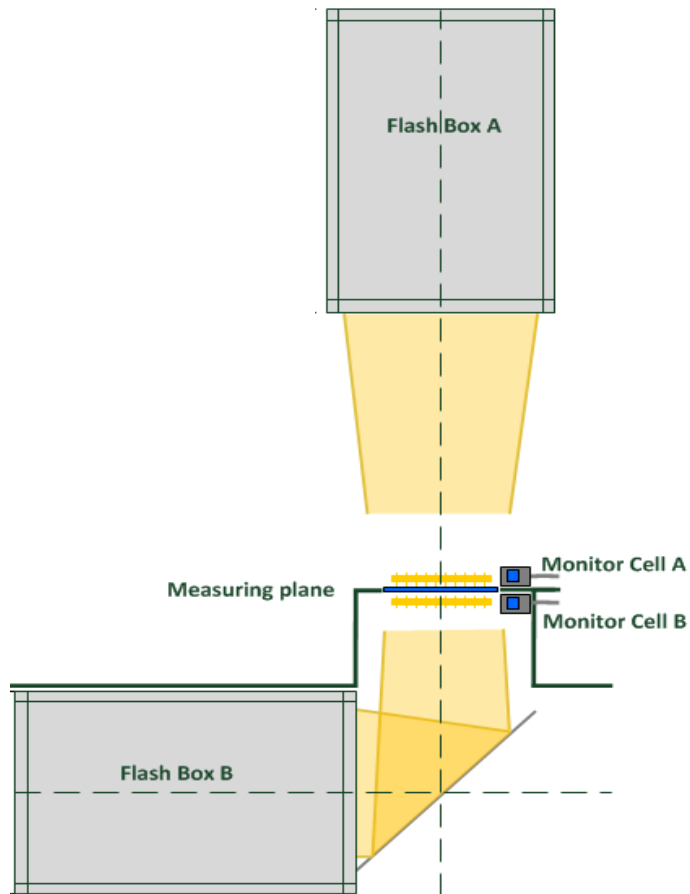
PC1D simulation of impact of parameter variations on front and rear efficiency

IV – parameters of base-cell simulated:

V_{OC} : 668.7 mV; J_{SC} : 39.56 mA/cm²; Eta: 22.04 %

Bifacial h.a.l.m. flasher solutions – solar cells

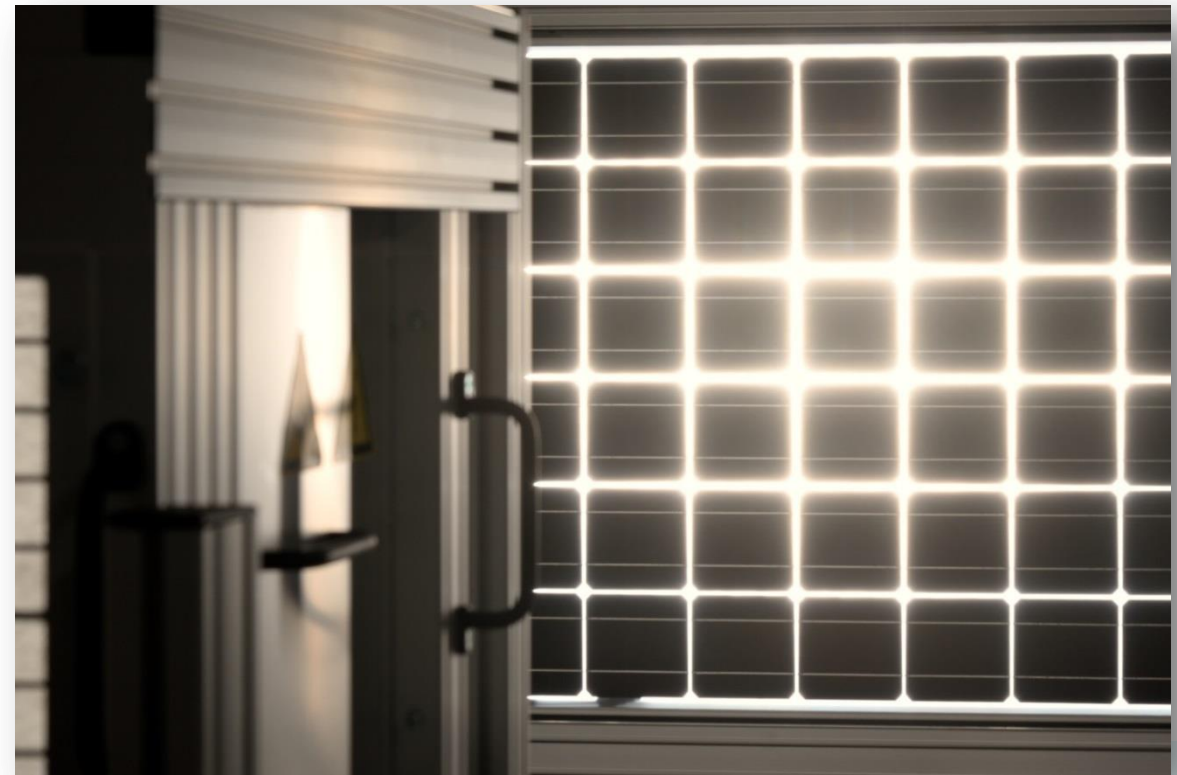
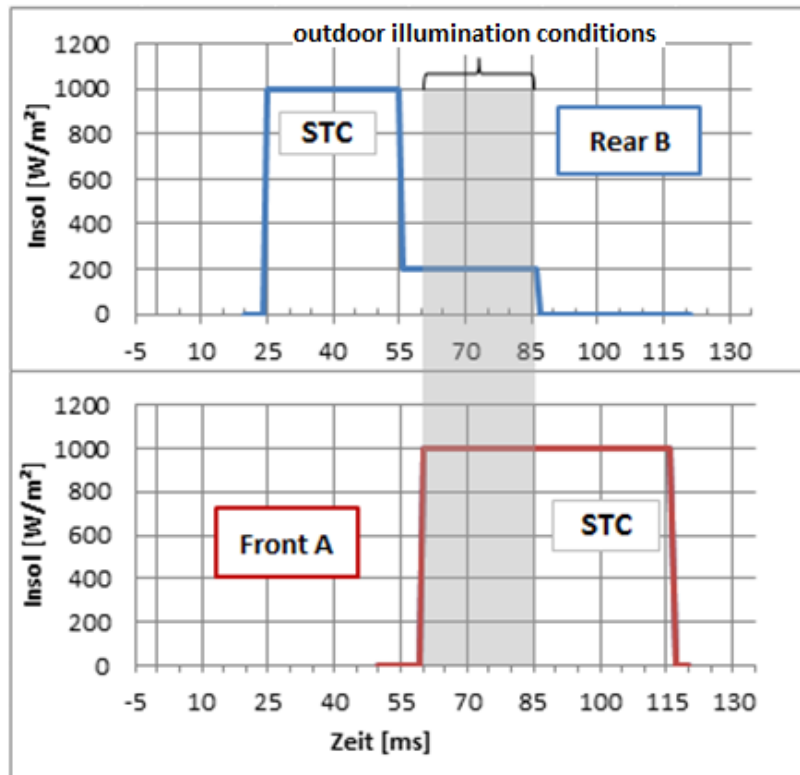
h . a . l . m .



- **One** IUCT-3600 **electronic cabinet**
- 2 flash boxes, one of them directed to the rear side of the cell via mirror
- One **measurement electronic**
- Light sources are synchronized and independently regulated
- Allows for **maximum variability** in flash sequence

Bifacial h.a.l.m. flasher solutions – flash sequence . h . a . l . m .

- One flash sequence allows illumination from front, rear and bifacial within 90 ms



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Contacting challenges for new cell designs

- Metallization layouts diversified
- More flexible contacting solutions required
- Contacting of cell fingers for busbarless cells
- Bifacial contacting
- Shingling
→ front and rear contacts not at same position
- More busbars
→ more shadowing

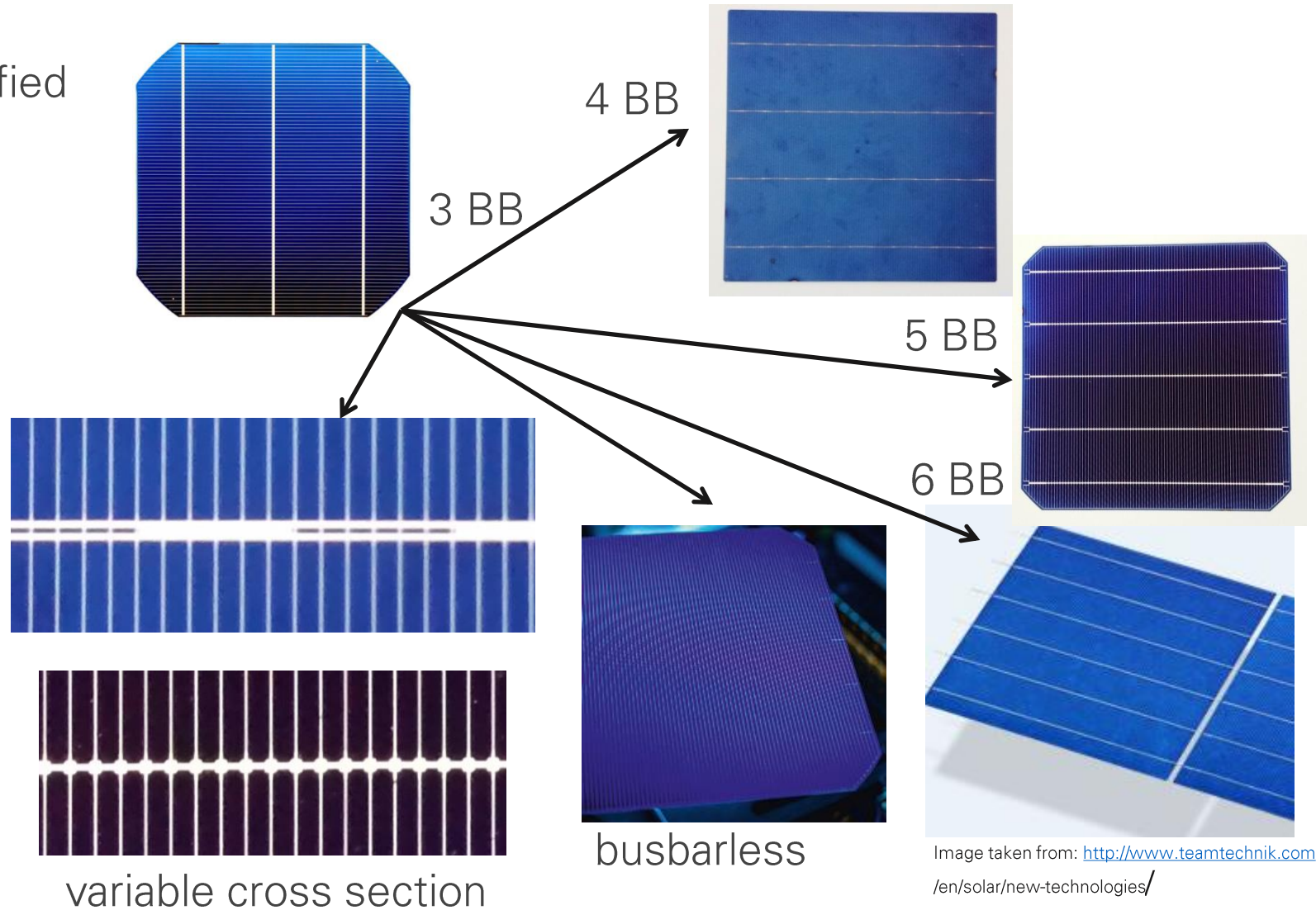
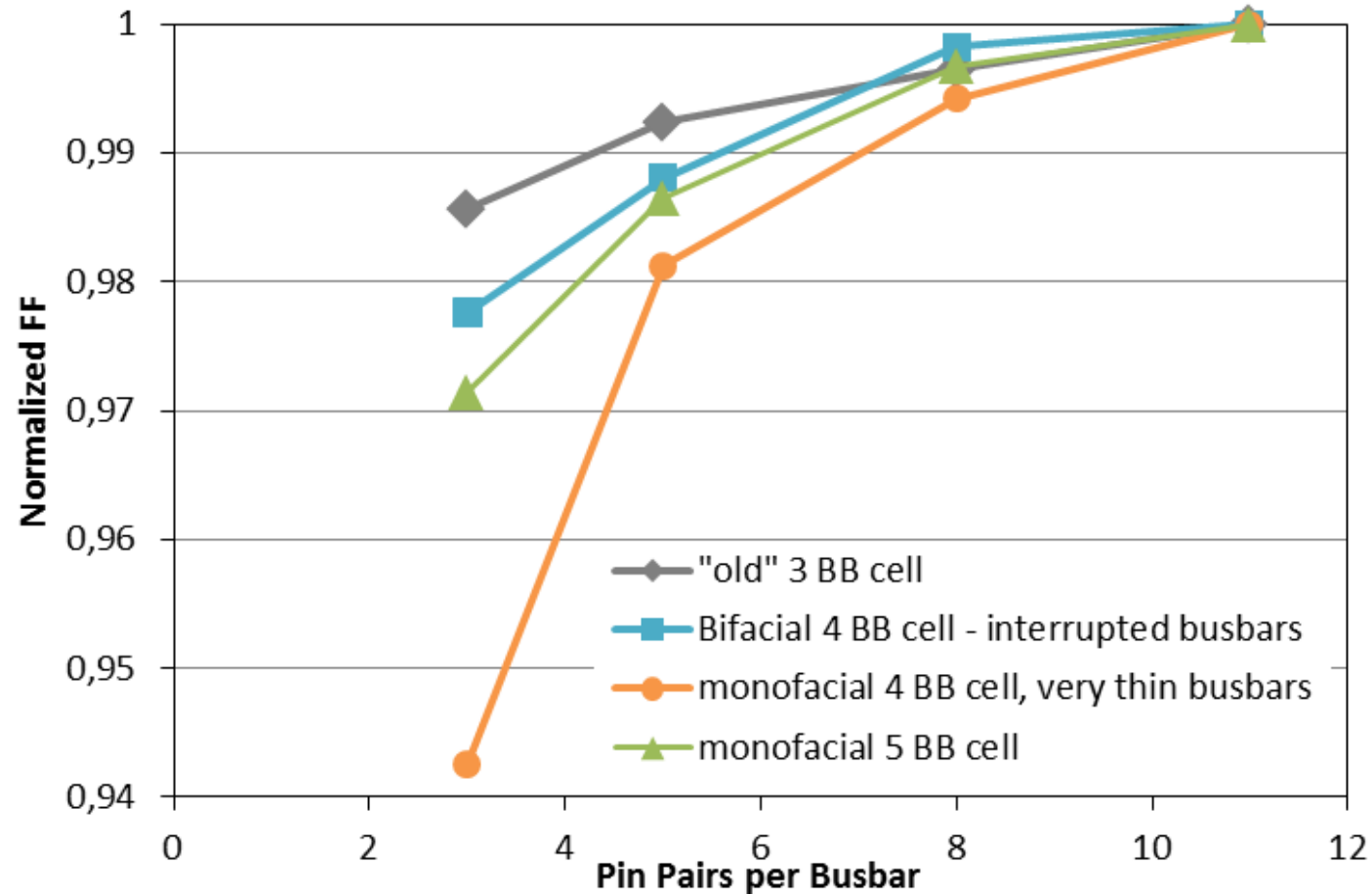


Image taken from: <http://www.teamtechnik.com/en/solar/new-technologies/>

Contacting challenges – busbar conductivity

Measured dependence of FF on number of probe pairs



- Strong dependence of FF on busbar conductivity
- Precise FF measurement requires large number of probe pairs

Contacting challenges – busbar layout

. h . a . l . m .

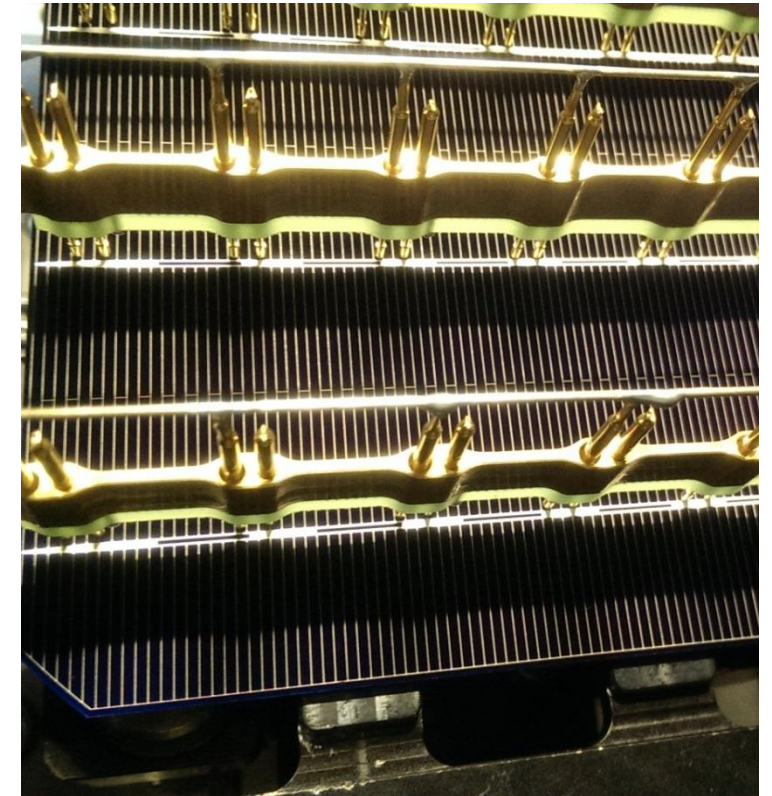
Interrupted Busbars – how to place the probes?

- probes must be placed on „solder“ islands
→ possibly limits number of probes

Busbarless cells

- Fingers need to be contacted directly

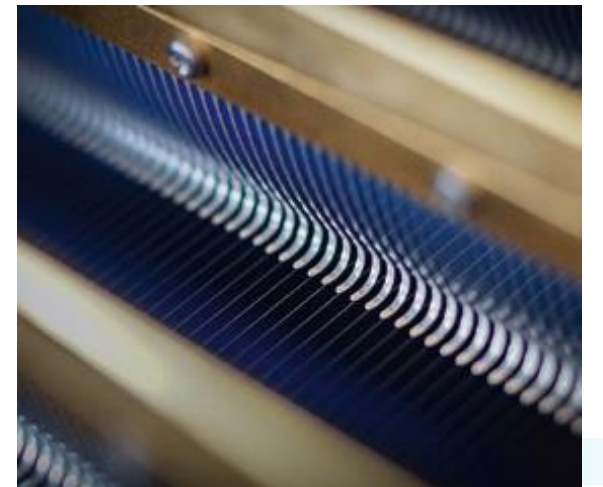
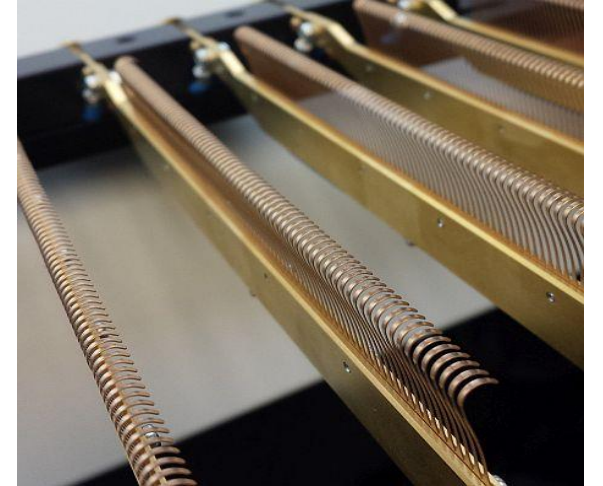
Reliable solution for different grid layouts required



h.a.l.m. solution for busbar independent contacting

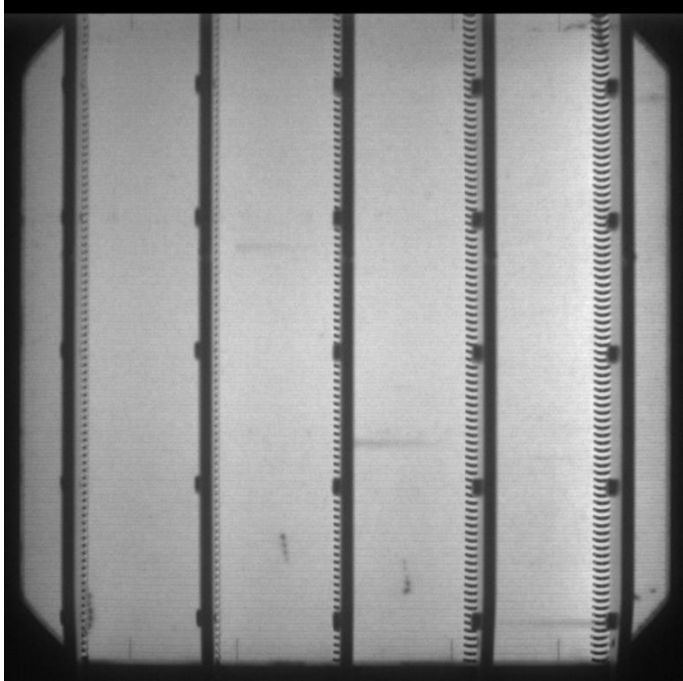
h . a . l . m .

- Large number of probes per busbar
- Probes independent from busbar design
- Suitable tapered or interrupted busbars
- Enables contacting busbarless cells in mass production
- Calibration of cells easy and compatible to existing solutions

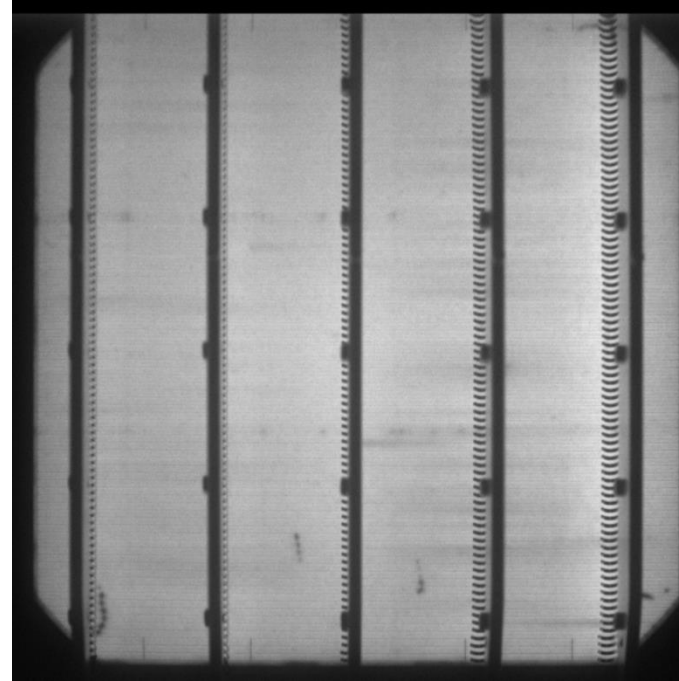


EL – imaging to check contacting quality on busbarless solar cells

h.a.l.m.



$I = 1.2x I_{sc}$



$I = 2x I_{sc}$

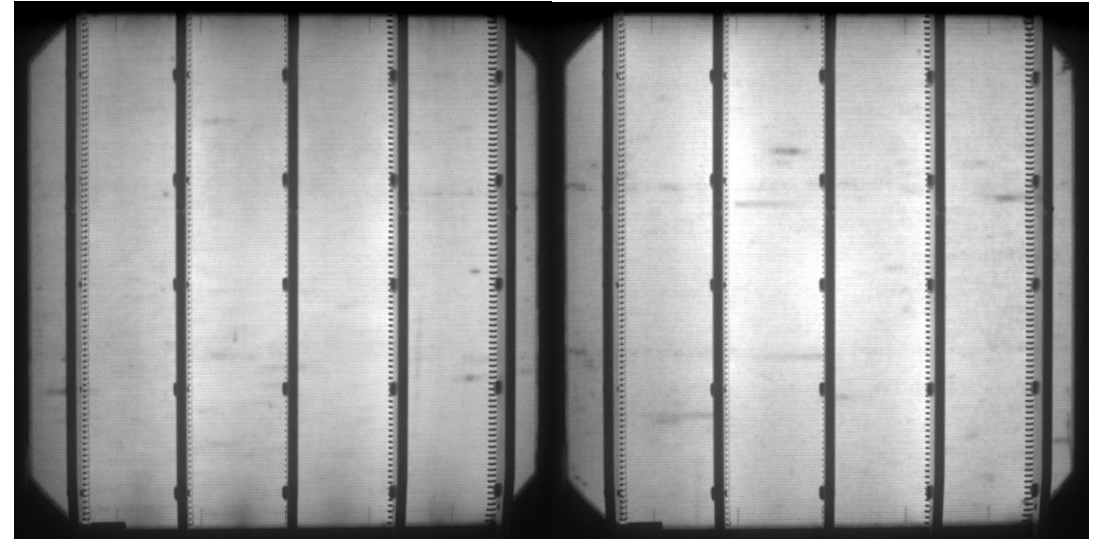
- Measurement on the same cell
- Contact is very homogeneous, only few of contacts which are not perfect

Reliability – EL imaging after 4 million contacting cycles . h . a . l . m .

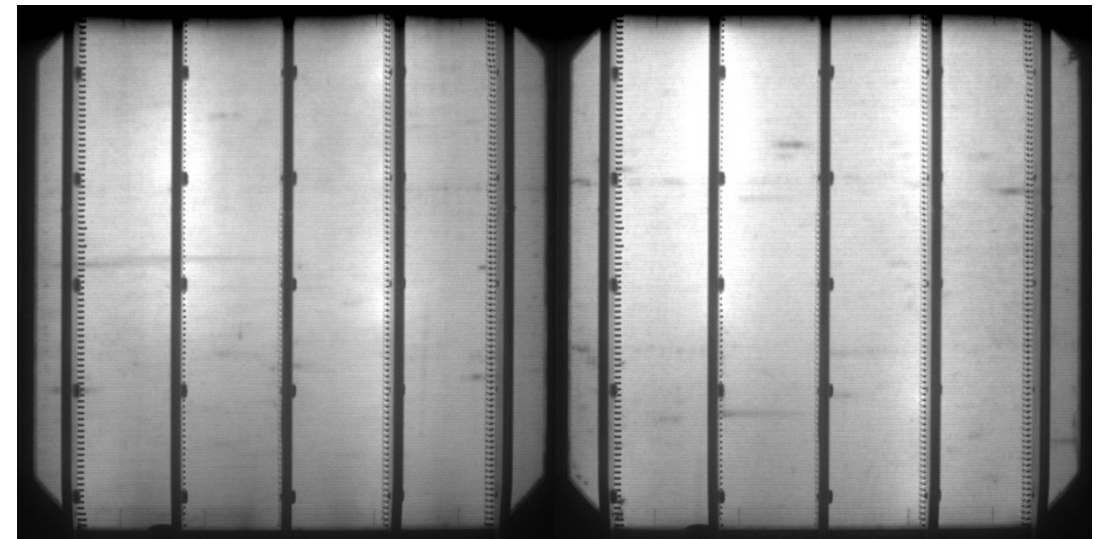
- Long – term test of contacting unit, with 4 million mechanical cycles
- Measurements on reference cells to check contacting quality
- Contacting performed on non-busbar areas of dummy cells
- Series resistance before test: 2.57 mOhm, after test: 2.69 mOhm

→ **very low wearing of the probes**

Before test



After test



Conclusion

————— Contact time e.g. 350 ms —————

Comm- unication	Light – IV (60 ms)	Dark – IV (60 ms)	Reverse – IV + TG	Electrolumines- cence (40 ms)	Inline-SR	Grid-Resistance	Comm- unication
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Example for hetero-junction technology, 60 ms IV-sweeps required, but EL is fast

————— Contact time e.g. 350 ms —————

Comm- unication	Light – IV (30 ms)	Dark – IV (30 ms)	Reverse – IV + TG	Electroluminescence (100 ms)	Inline-SR	Grid-Resistance	Comm- unication
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Example for PERC technology, IV-sweeps shorter, but EL needs more time

Sequences including all shown methods are possible in ≤ 350 ms

Conclusion

. h . a . l . m .

- Fast evolution of crystalline silicon PV technology results in a **variety of cell designs** with **more complex process sequences**
- Steadily increasing cell efficiencies cause a **higher sensitivity** to **material properties** and **process deviations**
- Light IV-curves of **high capacitance cells** can be measured precisely with **single flash ≤ 60 ms** using advanced hysteresis method

Conclusion

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- **Advanced inline characterization** methods are required to:
 - **Improve quality control** (eg. IV, hotspot, cracks)
 - Ensure **high yield** through better process control (eg. recombination losses, metallization)
 - Enable **fast ramp-up** of new production lines and new technologies

High throughput inline characterizations methods are available